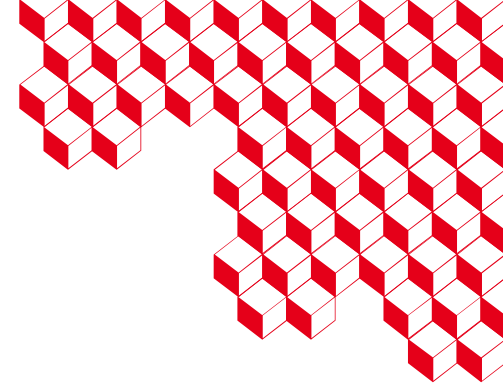




irfu



# Timing with Monolithic CMOS Potential applications to CEPC

CEA/Irfu/DphP and CEA/Irfu/Dedip

Yavuz DEGERLI, Fabrice GUILLOUX,

Jean-Pierre MEYER, Philippe SCHWEMLING (also  
Université Paris Cité)



Université  
Paris Cité

Tomasz HEMPEREK (U. Bonn, now at DECTRIS)

# Timing sensor basic ingredients

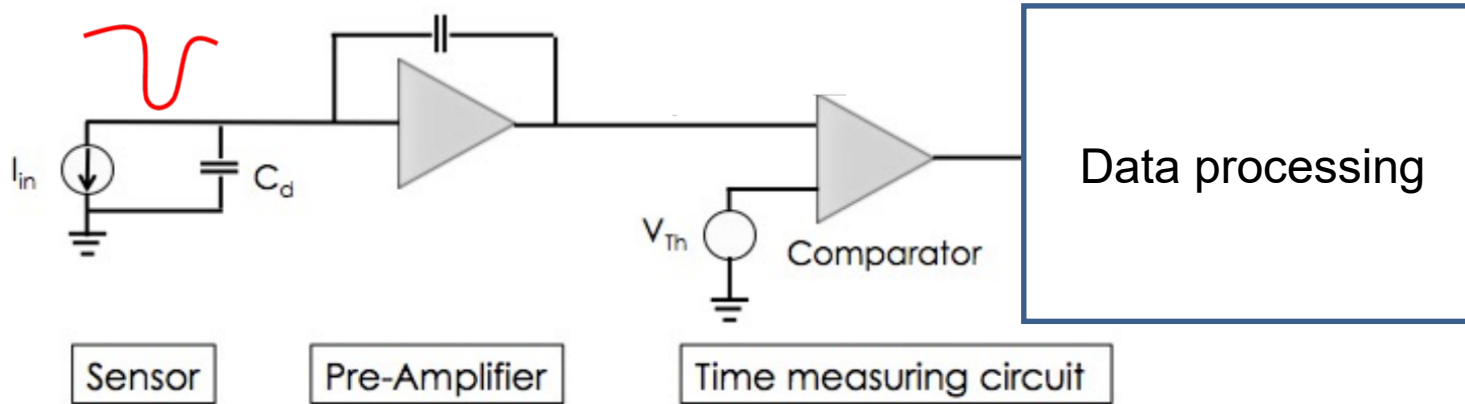
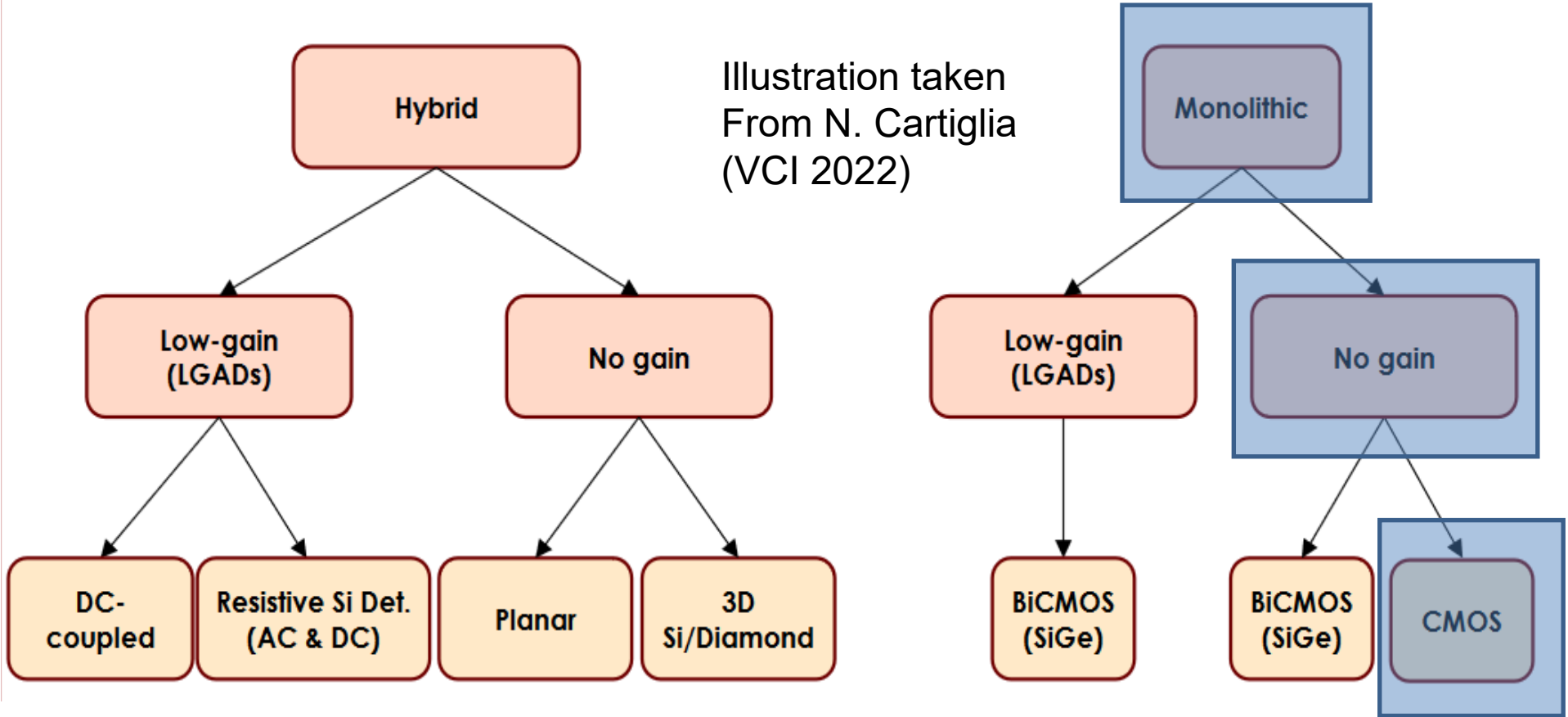


Illustration taken  
From N. Cartiglia  
(VCI 2022)

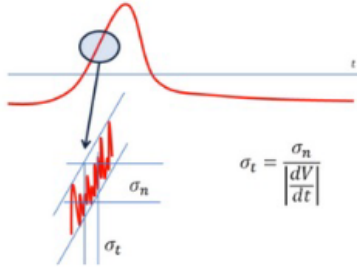
- Monolithic sensors : Analog Front-End, Time measuring electronics (typically LE discriminator)
- Data processing (TDC, serializers, PLL, sparsification) can ideally also be on same chip, but actual development not easy (risk of analog/digital couplings)

# Timing oriented sensor families



# Time resolution

$$\sigma_t^2 = \left(\frac{\text{Noise}}{dV/dt}\right)^2 + (\Delta\text{ionization})^2 + (\Delta\text{shape})^2$$



$$\sigma_t = \frac{\sigma_n}{\left|\frac{dV}{dt}\right|}$$

“Jitter” term

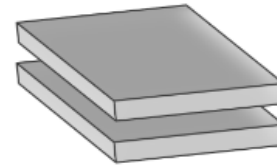
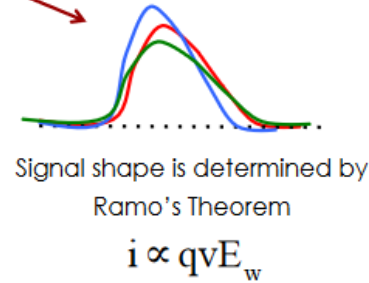
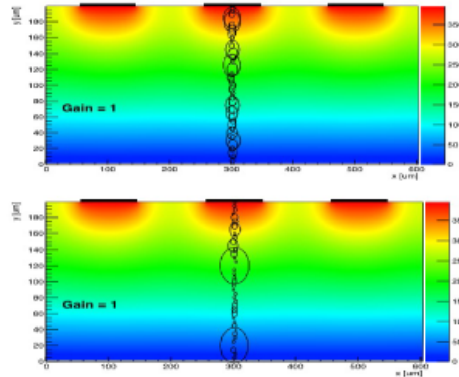


Illustration taken  
From N. Cartiglia  
(VCI 2022)

Small noise  $\rightarrow$  choice of  
technology, small detector  
capacitance

High  $dv/dt \rightarrow$

High electric field (but  $Vd$   
saturates around  $1 \text{ V}/\mu\text{m}$ )

Intrinsic amplification (LGADs)

Amplitude variation  $\rightarrow$  Timewalk,  
corrected offline

Non-homogeneous energy  
deposition  $\rightarrow$  cannot be corrected,  
minimized by design

Saturated drift velocity  
in sensor volume  $\rightarrow$   
Uniform weighting field

Parallel plate geometry,  
easier for big pixels

# Features of monolithic CMOS sensors

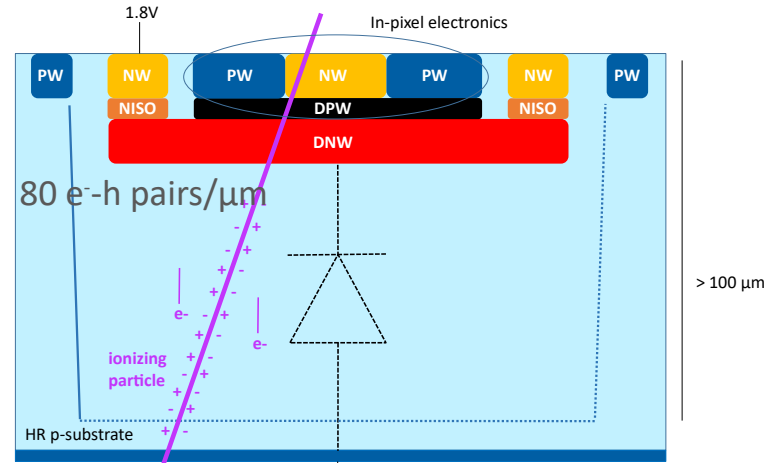
- (Relatively) cheap high volume industrial technology
  - 2-3 k euro/8" wafer, post-processing and dicing included → bare sensor cost for 100 m<sup>2</sup> : 7-11 M euros
  - Bump bonding operation not needed for fully monolithic architecture
- Stable and easy operation
- HV-HR wafers available, allows charge collection by drift and not only by diffusion → favorable for fast collection and also for radiation hardness
- Can be designed as a complete SoC, from sensor to DAQ interface
- Presently available technologies are known to be rad-hard up to a few 10<sup>15</sup> 1 MeV neq/cm<sup>2</sup>
- Can be thinned down to < 100 μ

# TIMING WITH HV-CMOS/DMAPS\*

\*Depleted MAPS

- ❑ The objective of our R&D is the development of a **monolithic timing sensor** in a **commercial HV-CMOS process** for future high energy physics experiments or for LHC upgrades (timing detectors, after phase 2 upgrades)
- ❑ **LFfoundry 150 nm HV-CMOS** is one of the CMOS processes studied extensively for the CMOS option of the ATLAS Inner Tracker Upgrade
- ❑ Several large size demonstrators already designed and tested for tracking applications (**LF-CPIX**, **LF-MONOPIX1**, **LF-MONOPIX2**) in this process with proven **radiation hardness** (Bonn, IRFU and CPPM coll.)

## HV-CMOS Sensor Pixel

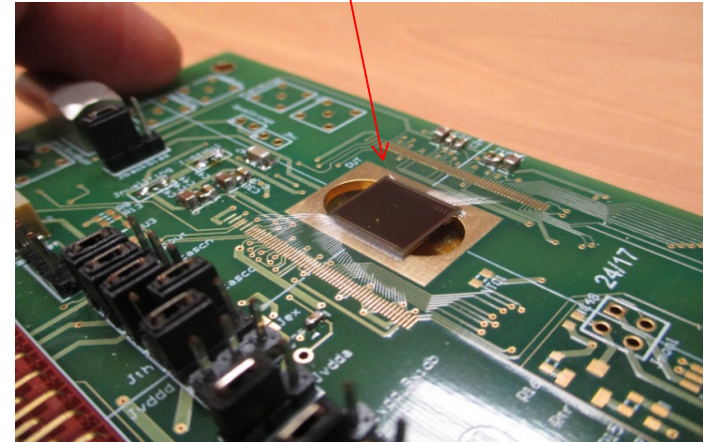
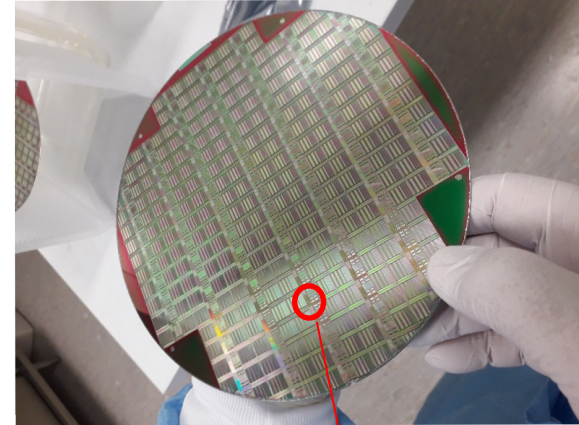


- DNW/HR p-substrate charge collection diode
- HV ( $\geq 300 \text{ V}$ ) applied on the substrate (from top or back)
- Large depletion depth ( $\geq 300 \mu\text{m}$ )
- **Charge collection by drift (fast)**
- **No internal amplification**
- Electronics can be integrated inside charge collection diode

# CACTUS\* DEVELOPMENT

- ❑ The first demonstrator called **CACTUS** for timing in LF 150 nm process designed in 2019
- ❑ The front-end in CACTUS is based on an **in-pixel fast preamplifier** followed by a **leading edge discriminator**
- ❑ Time walk corrections done off-line by **ToT measurement**
- ❑ Expected timing resolution from Cadence & TCAD simulations: 50-100 ps

\*CMOS Active Timing  
 $\mu$ Sensor



The CACTUS demonstrator on PCB  
(chip size : 1 cm x 1 cm)

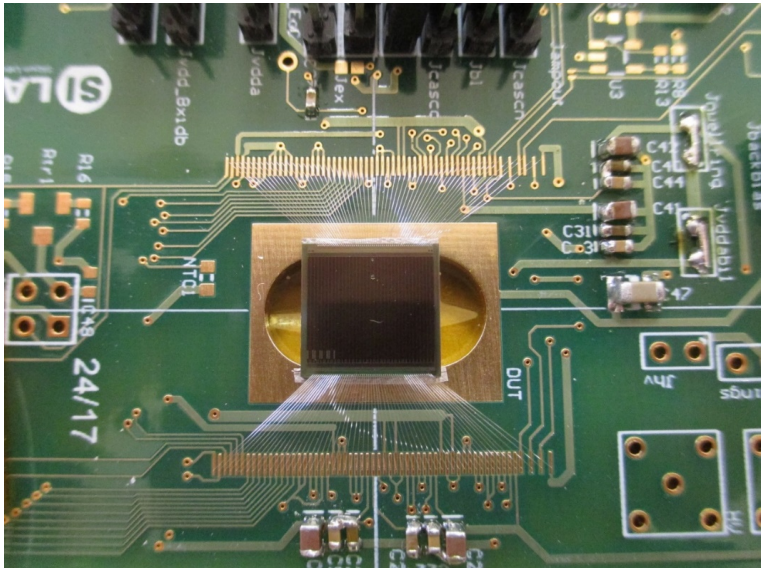
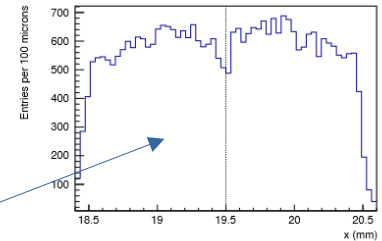
# Cactus (Irfu) : Timeline and results

We started around 2017 after being involved into LF-CPIX and MONOPIX strip detector for ATLAS-ITK outer layers (possible backup solution).

CACTUS was designed in parallel, reusing blocks and concepts from LF-CPIX and MONOPIX, adding optimizations towards timing performance

At that time, 2 possible applications for sub-100ps timing detectors:

- ATLAS High  $\eta$  muon tagger (upstream forward calorimeter)
- HGTD in front of ATLAS-LAr



First try with CACTUS:

- Yield correct, High break down voltage, homogenous charge collection, deep depletion depth

- Main problem with CACTUS: **underestimation of parasitic capacitance** → bad S/N

-Also coupling between analogic and digital part → ringing of digital pulse

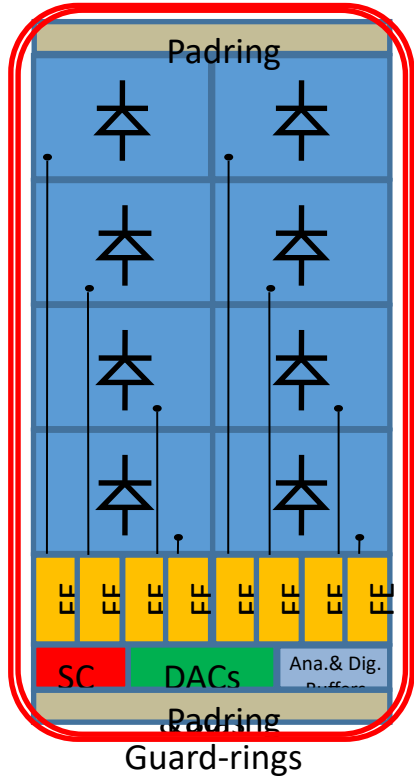
→ modest timing performance ~500ps

<https://arxiv.org/abs/2003.04102>

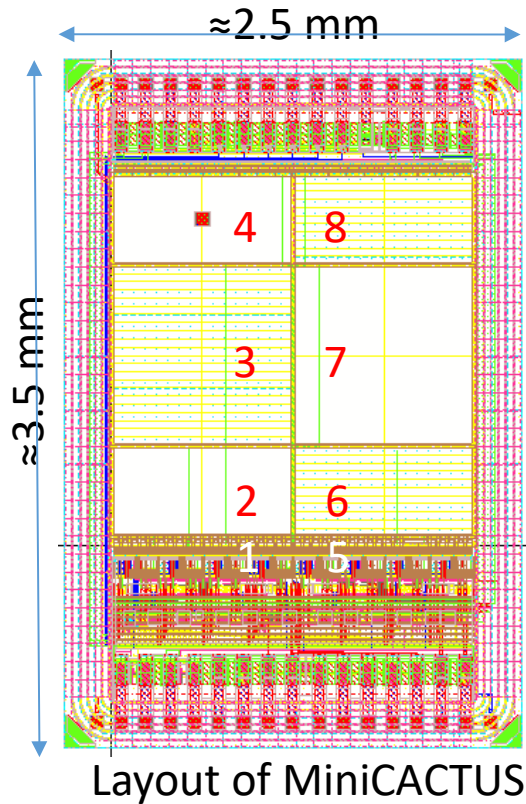
→ Version 2 of CACTUS called Mini-Cactus



# MiniCACTUS Sensor Chip



Block diagram of the MiniCACTUS chip (not to scale)

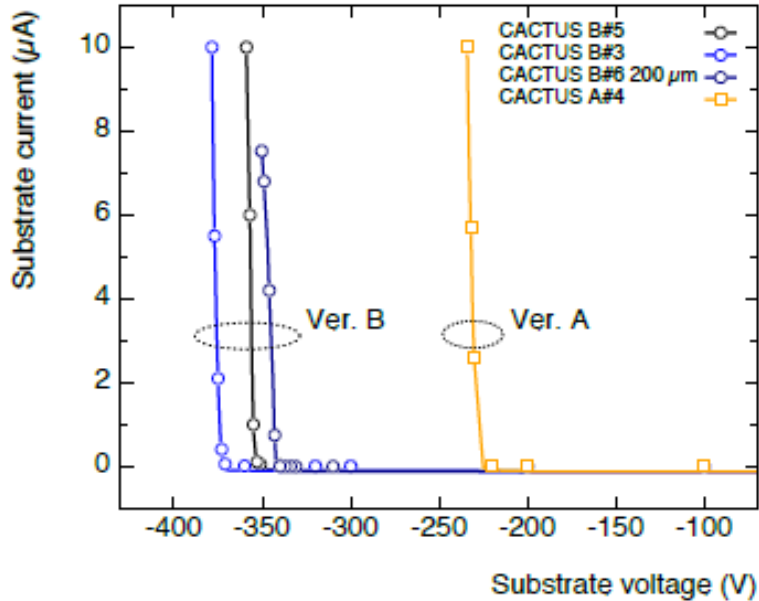


- Pixel Flavors :**
- Pixels 3 & 7 : 1 mm x 1 mm baseline pixels
  - Pixels 2, 4, 6 & 8 : 0.5 mm x 1 mm pixels
  - Pixel 8 : 0.5 mm x 1 mm pixel with in-pixel AC coupling capacitor (20pF)
  - Pixels 1 : 50  $\mu\text{m}$  x 50  $\mu\text{m}$  test pixel
  - Pixels 5 : 50  $\mu\text{m}$  x 150  $\mu\text{m}$  test pixel

- MiniCACTUS is a smaller detector prototype designed in order to address the *low S/N issue* observed on previous CACTUS large size demonstrator
- Main change in MiniCACTUS: FE integrated at column level, pixels mostly passive
- On-chip **Slow Control, DACs, bias circuitry**
- 2 discriminated digital (LVDS) and 2 analog monitoring (*slower than CSA output*) outputs for 2 columns
- 2 small pixels implemented as test structures to study charge collection (*FES not power optimized*)
- Some detectors thinned to 100, 200, 300 $\mu\text{m}$  and than post-processed for backside polarization after fabrication

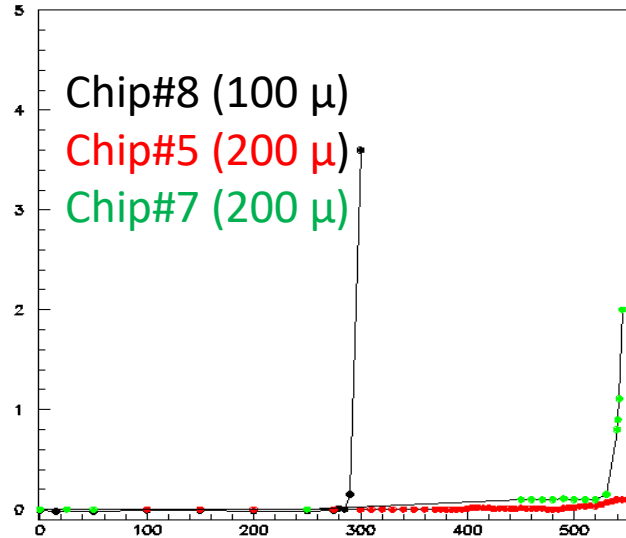
# BREAKDOWN VOLTAGE MEASUREMENTS

## CACTUS



- Found similar BV for thinned and unthinned chips
- Version B BV is around 350 V.

## MiniCACTUS

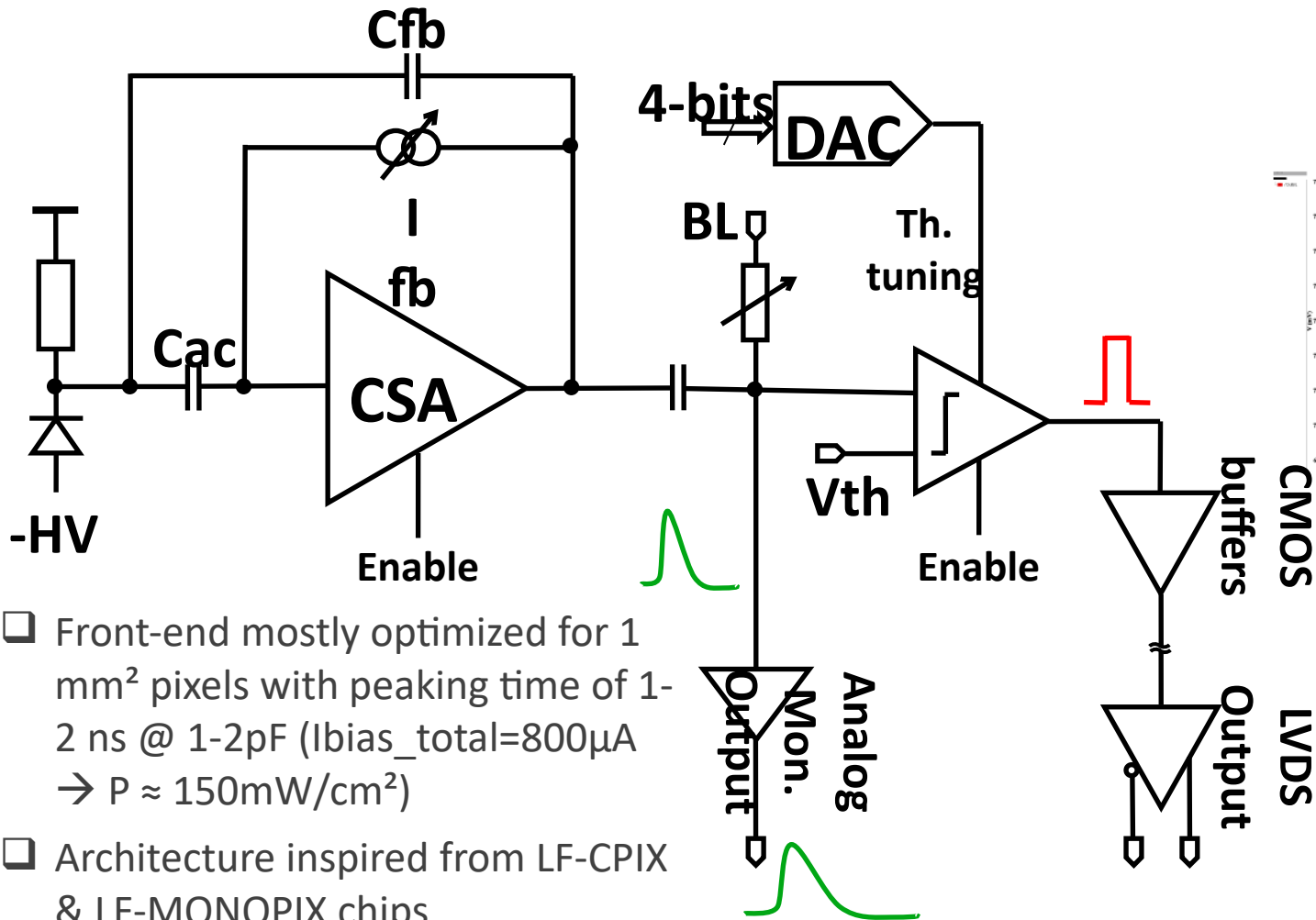


- Same LF15A process used for both chips
- Same guard rings used for both chips (MiniCACTUS uses Ver. B CACTUS rings)
- Same postprocessing for both chips (as far as we know)

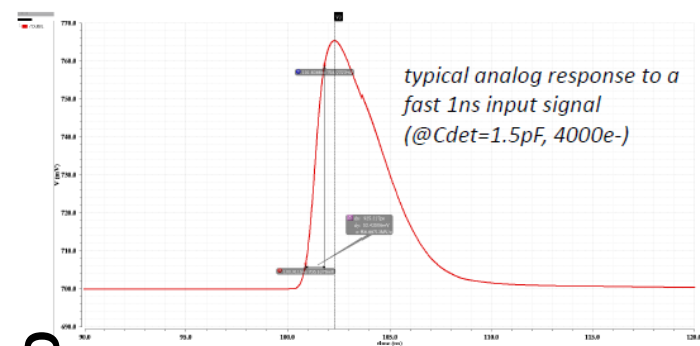
The tested two 200 μ chips break down above 500 V !

Not clear why there is such a difference between 200 μ chips and other thicknesses : post-processing details ? Specific wafer ?

# ON-CHIP FRONT-END



Typical CSA transient simulation result

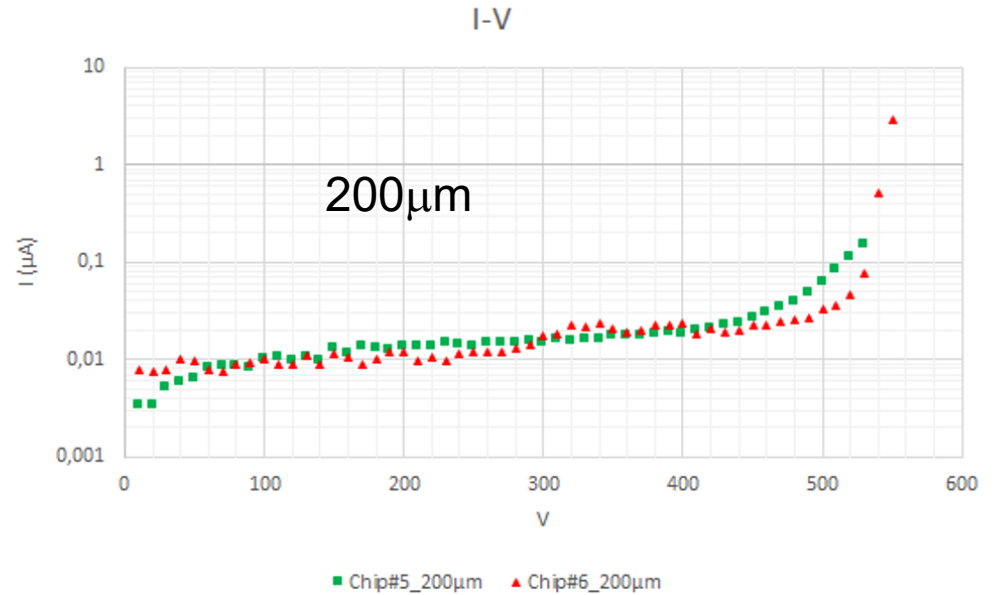
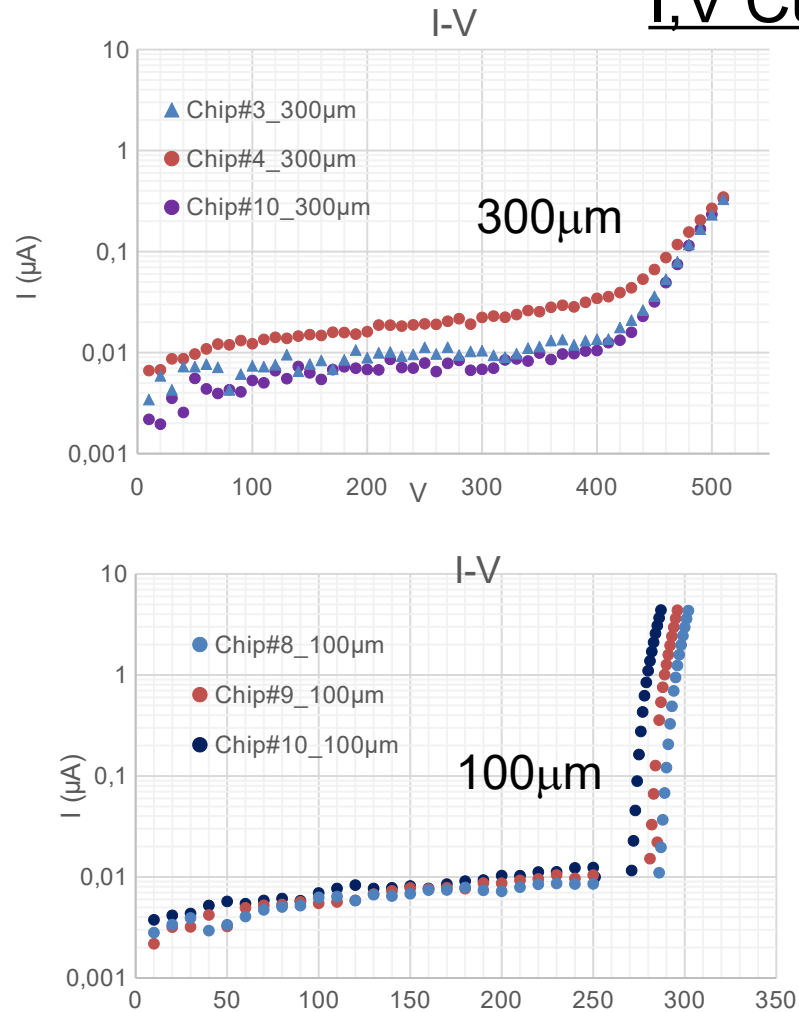


Parameter	1.5 pF	1 pF
Rise Time (from 10% to 90%)	~ 0.9 ns	~ 0.8 ns
Input Referred Noise [estimated from AC simulations]	~ 290 e-	~ 220 e-
Jitter [estimated from $t_r/(S/M)$ ]	~ 67 ps	~ 44 ps

- Front-end mostly optimized for 1 mm<sup>2</sup> pixels with peaking time of 1-2 ns @ 1-2pF ( $I_{bias\_total}=800\mu A \rightarrow P \approx 150mW/cm^2$ )

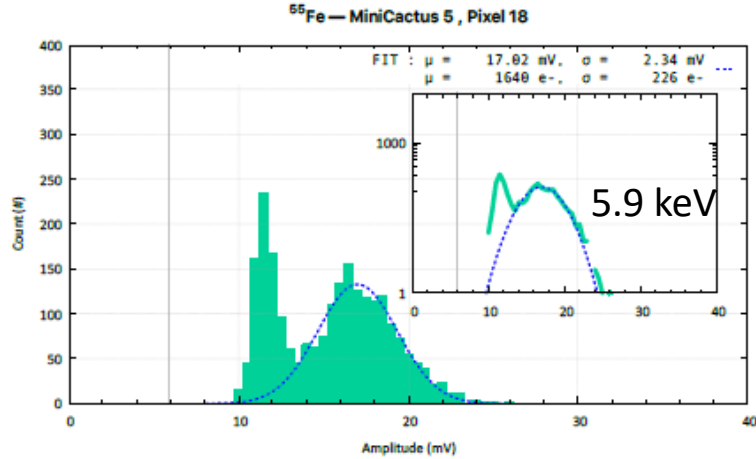
- Architecture inspired from LF-CPIX & LF-MONOPIX chips

# I,V Curves of MiniCactus



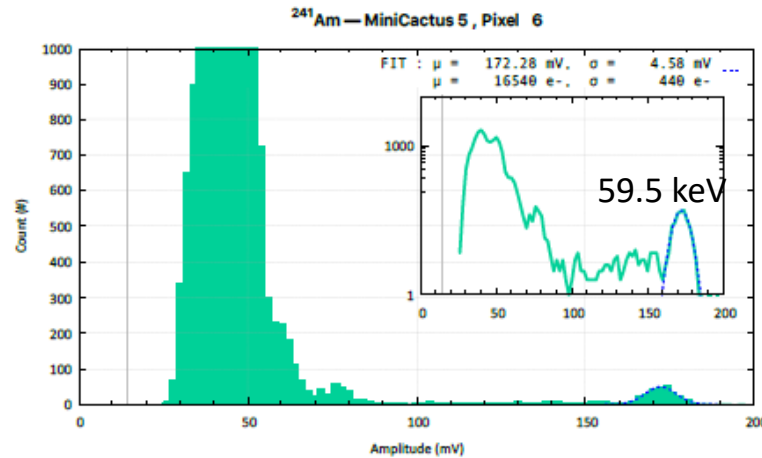
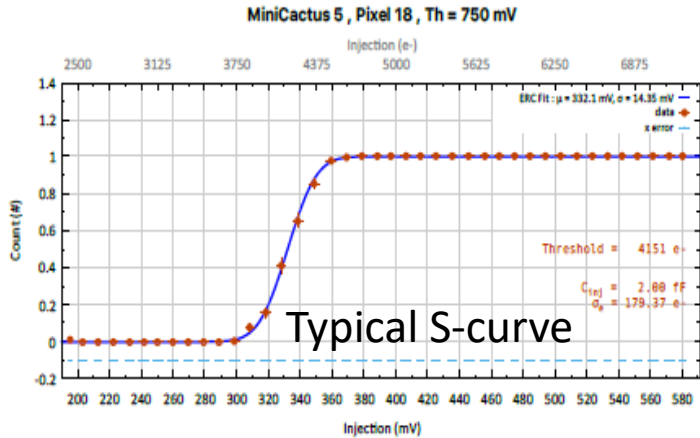
Breakdown voltage from 300 V to 500 V  
Variations likely due to posprocessing

# IN-LAB TESTS (injection pulse, Gamma-ray sources)

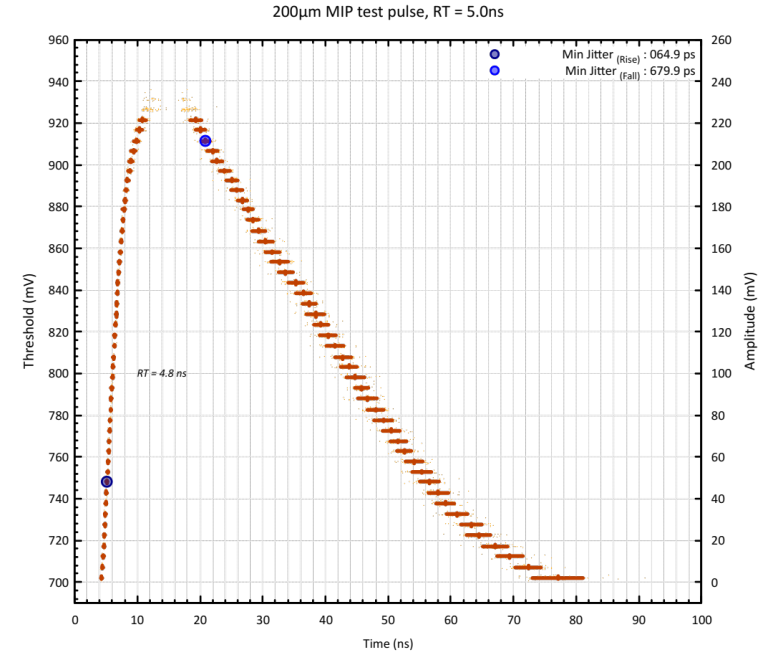
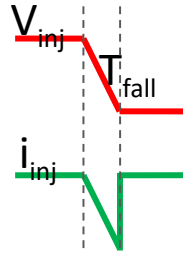
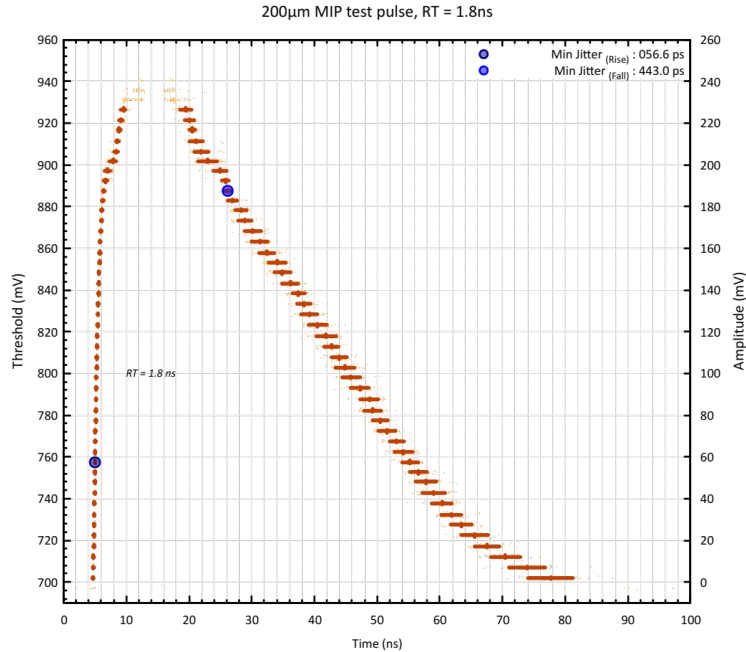


→ Best S/N observed on pixel 8 (0.5mm<sup>2</sup>) among large pixels

→ Noise<sub>t</sub>:  
 179.4e- (chip#5\_200μm)  
 155.9e- (chip#8\_100μm)



# INTERNAL ANALOG PULSESHAPE RECONSTRUCTION FROM DIGITAL OUTPUT



- Charge Injection  $\rightarrow$   $V_{peak}$  AmpOut  $\sim$  150 mV
- (MPV of MIPs for a 200  $\mu$ m thick sensor)
- Input injection pulse Rise/Fall Time = 1.8 ns
- FE Internal Pulse Rise Time  $\approx$  1.7 ns

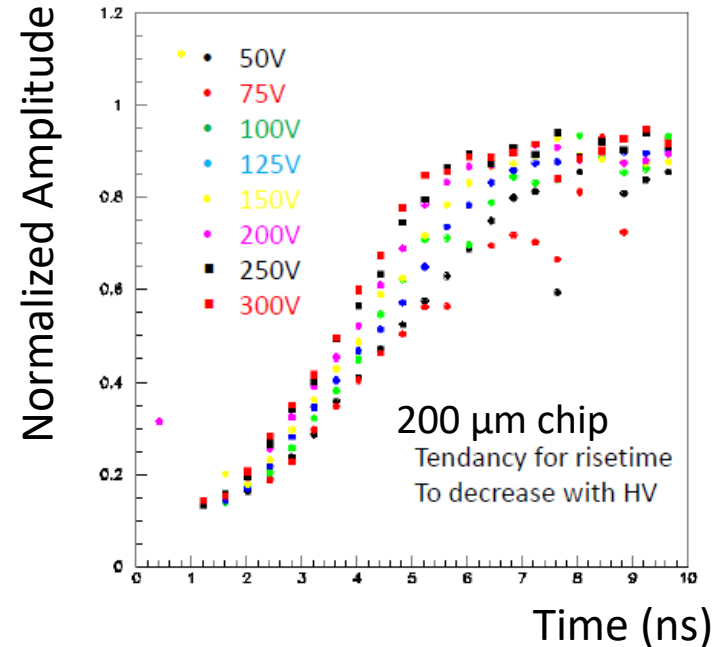
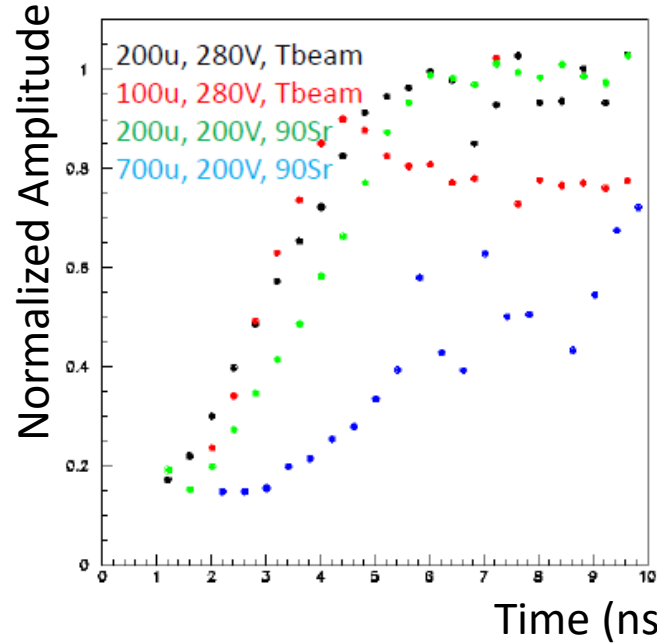
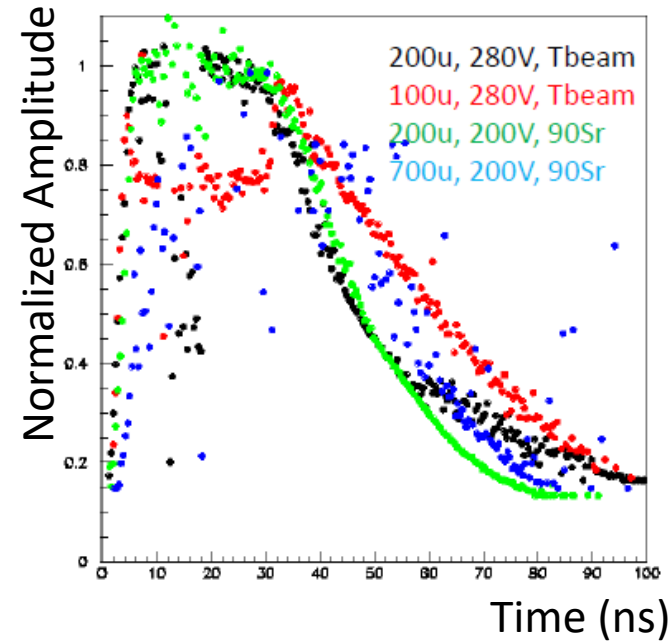
*s (not realistic case)*

$\rightarrow$  The FE follows well a 1.8 ns falling edge digital injection pulse

- Charge Injection  $\rightarrow$   $V_{peak}$  AmpOut  $\sim$  150 mV
- Input Rise/Fall Time = 5.0 ns
- Pulse Rise Time  $\approx$  4.8 ns
- Jitter : 64.9 ps

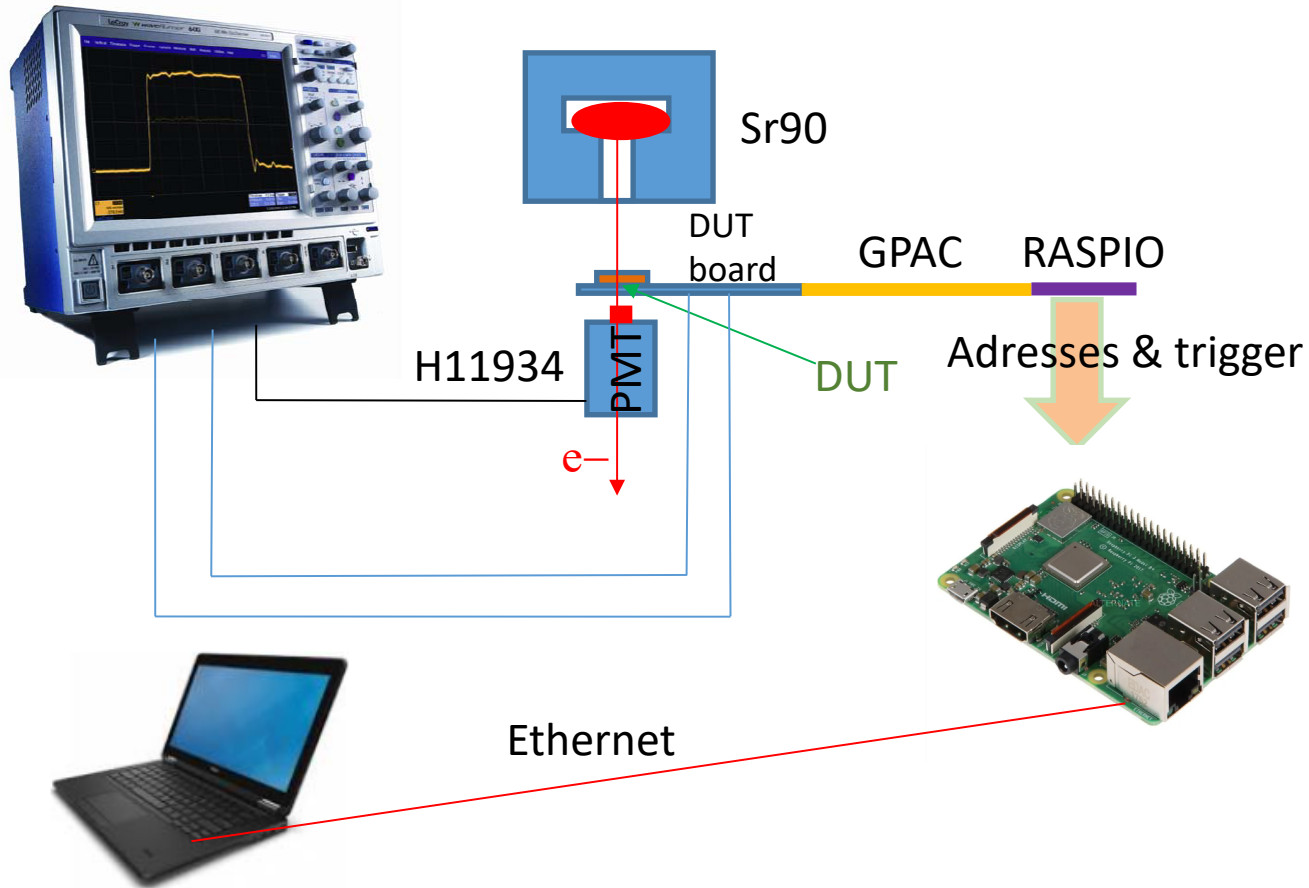
# INTERNAL ANALOG PULSES SHAPE RECONSTRUCTION ATTEMPT

## Testbeam data



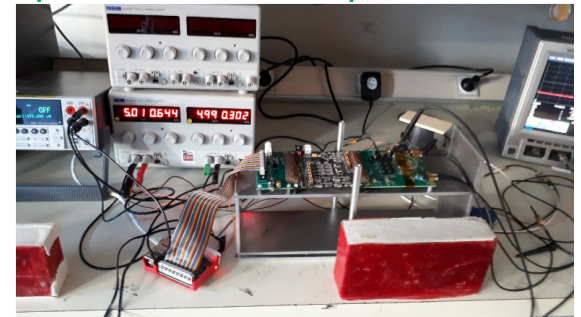
- Internal pulseshape reconstruction not very precise, but enough to get an idea of the shape and the rise time
- Rise time is of the order of **4-5 ns** for 200  $\mu$ m and 100  $\mu$ m  $\rightarrow$  need to reoptimize front-end for future iterations
- The unthinned 700  $\mu$ m chip are clearly slower  $\rightarrow$  post-processing is definitely needed !
- Rise time decreases somewhat with HV (related to drift velocity increase)
- With these results, for a given thickness and bias voltage, **the noise of the FE seems to be the limiting factor of the current timing resolution**

# IN-LAB $^{90}\text{Sr}$ TEST SET-UP



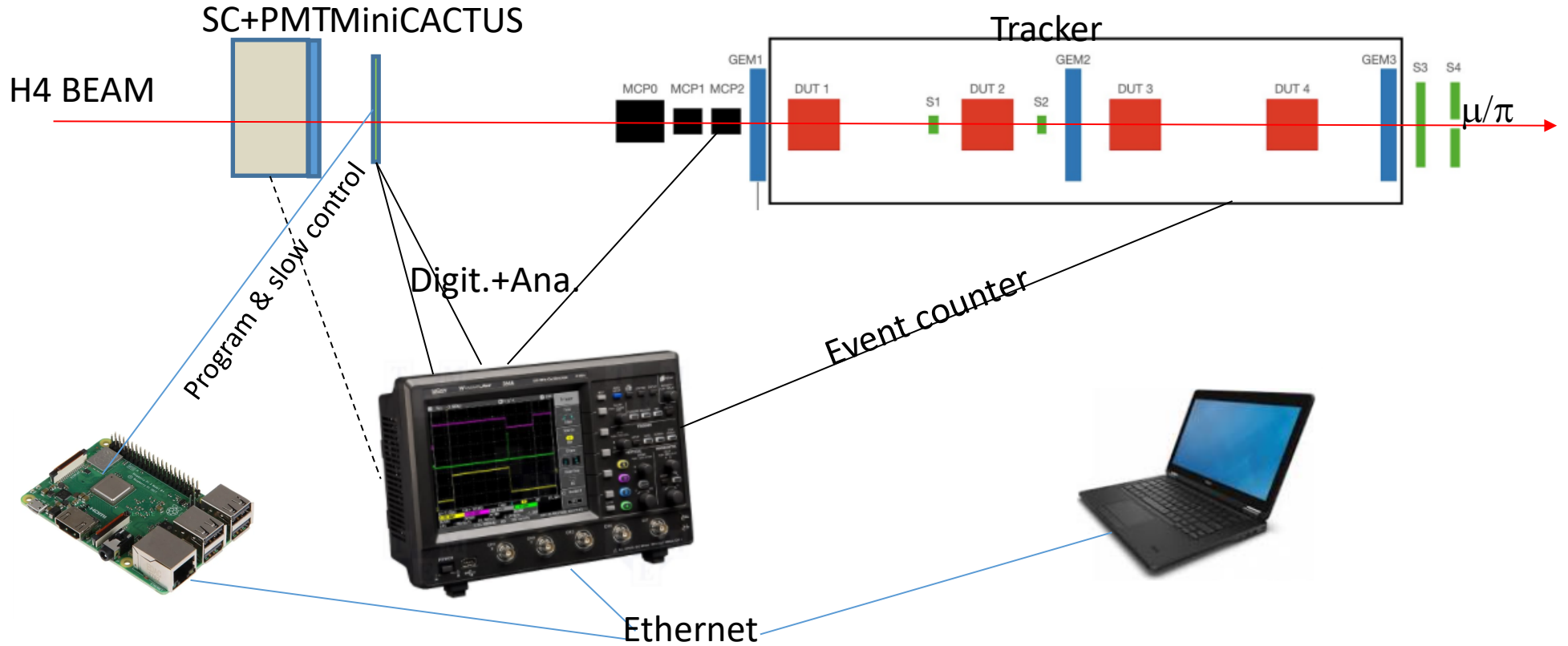
Used for :

- First test and debug
- Calibration
- parameter optimisation studies looking for relative performance improvements



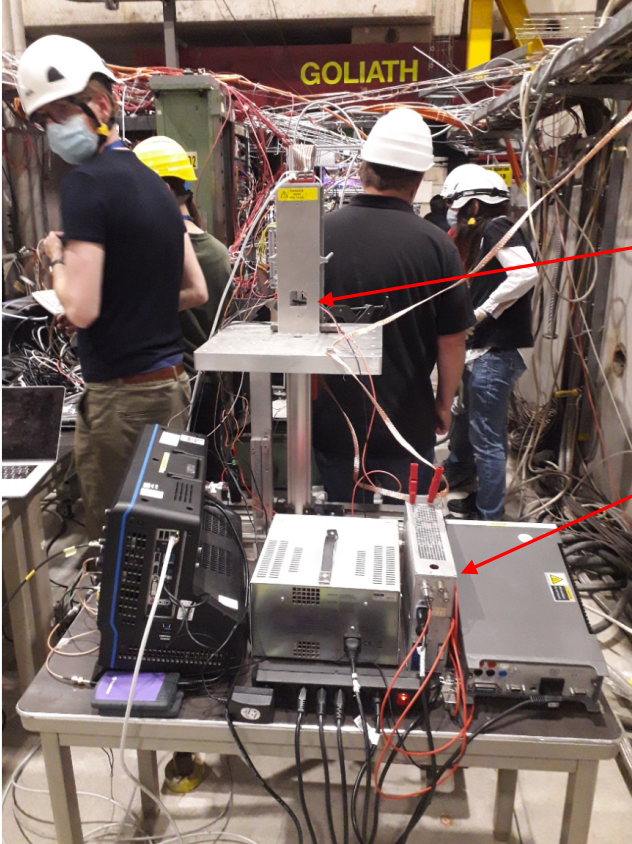


# TESTBENCH OF MINICACTUS IN TESTBEAM



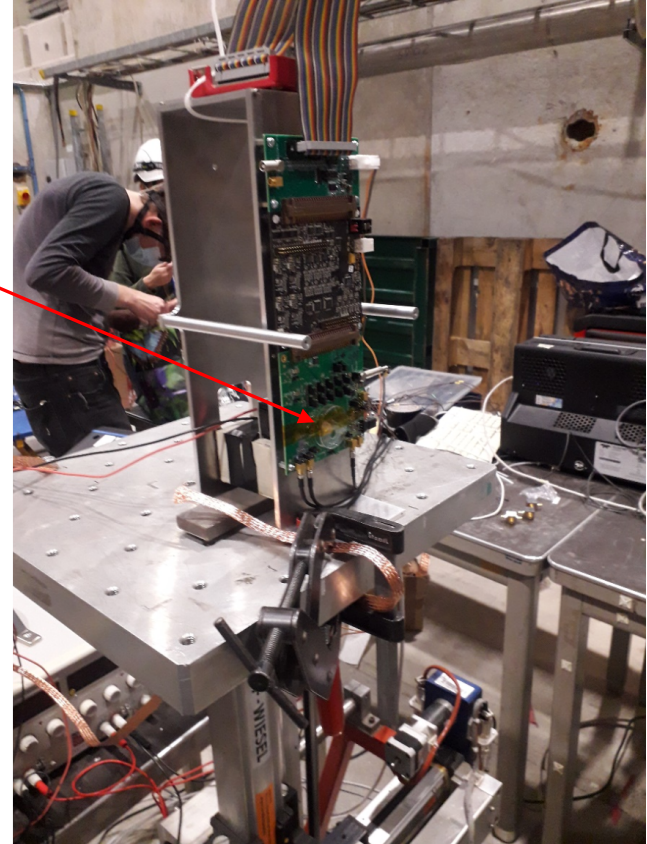
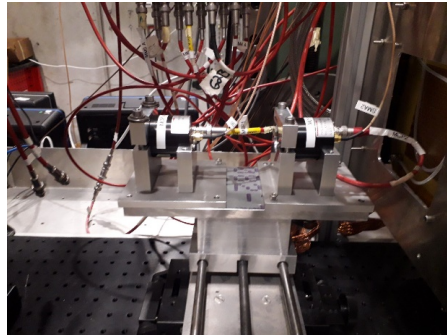
Setup installed on H4 line at SPS-CERN during **RD-51** test-beam periods in **parasitic** mode  
(October 2021, April 2022, September 2022)

# TESTBENCH OF MINICACTUS IN TESTBEAM



MiniCACTUS

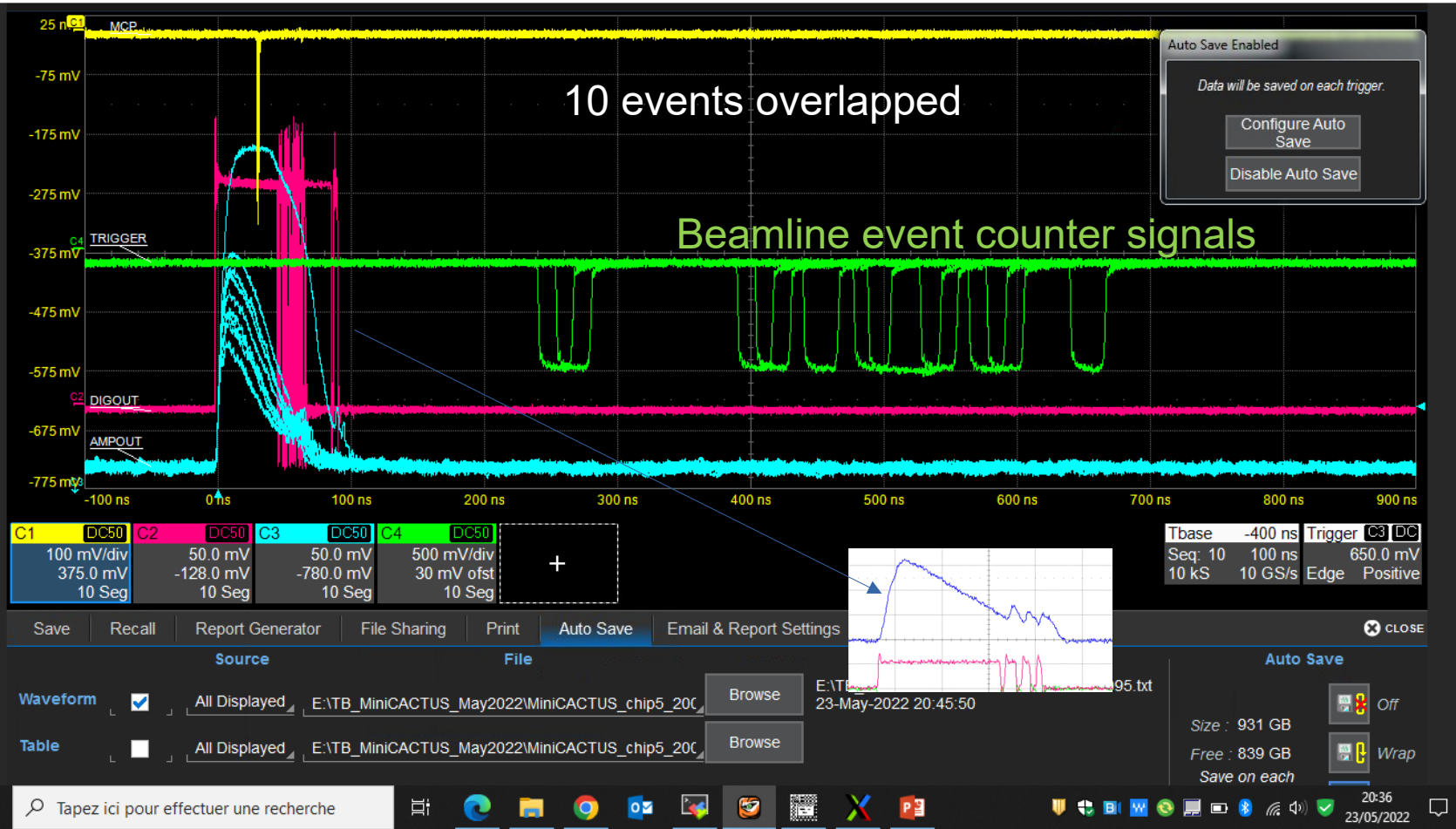
Power Supplies  
(LV and HV)



Time reference  
RD-51 MCPs (resolution  $< 10$  ps)

# TYPICAL WAVEFORMS OBSERVED DURING TESTBEAM

lcrn4204n20435 - TigerVNC@bxplus732.cern.ch

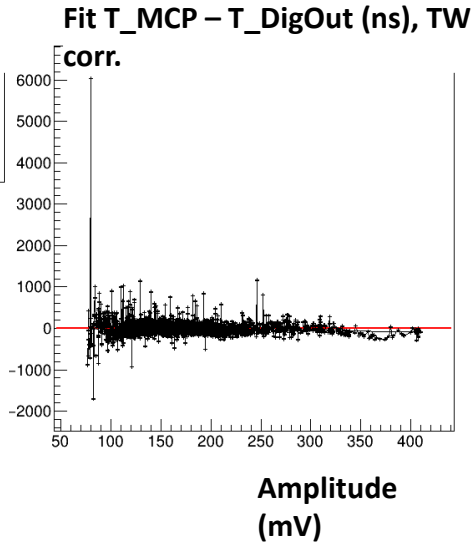
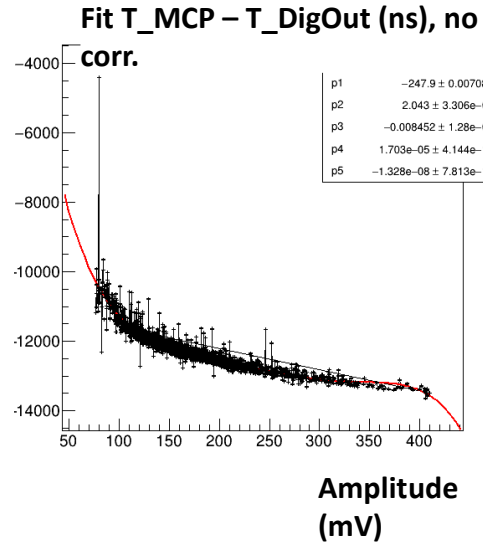
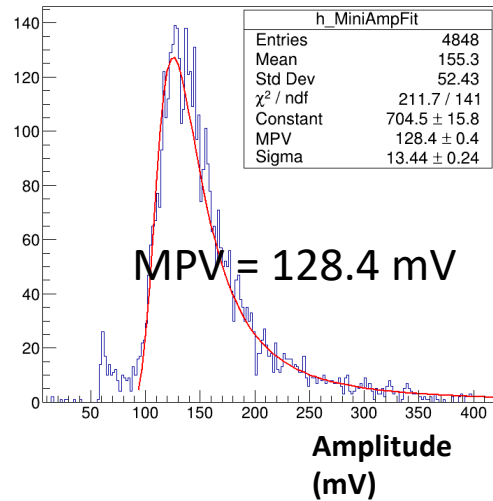


→ Ringing on Digital Output due to coupling from the digital buffers (known problem from in-lab tests, negative impact on TW corrections from digital ToT)

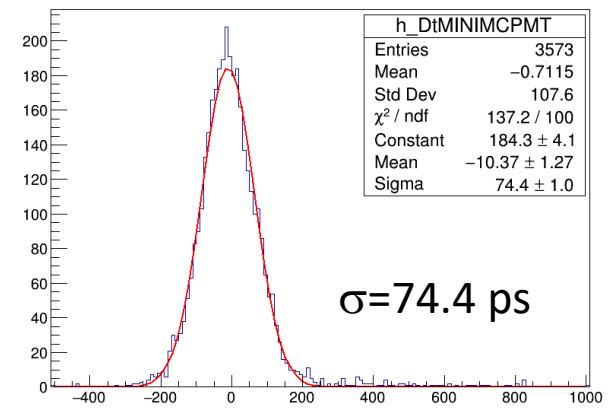
# DATA ANALYSIS PROCEDURE

Chip#5, pixel 8,  $0.5 \times 1 \text{ mm}^2$ ,  $200 \mu\text{m}$ ,  $-280\text{V}$  (Back-side pol.)

## MiniCACTUS Analog Monitoring Output



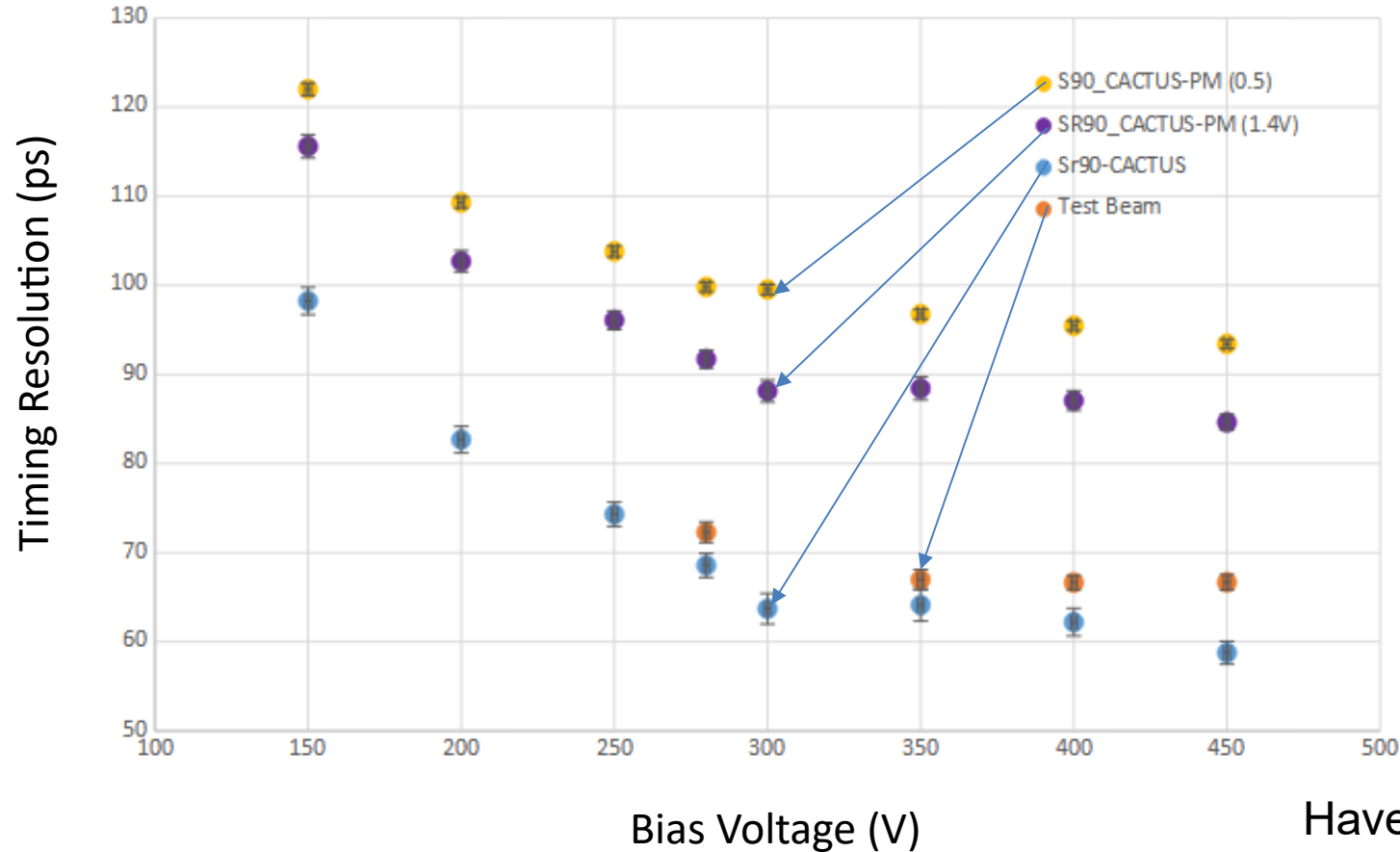
## $T_{\text{MCP}} - T_{\text{DigOut}}$ (ps) after TW correction



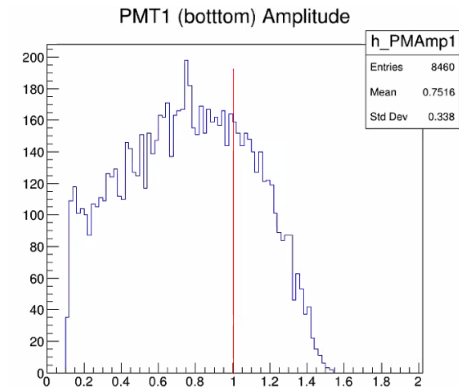
- Measured timing resolution ( $-280 \text{ V}$ ) : **74.4 ps** (MCP resolution negligible)
- Worse timing resolution measured with  $100 \mu\text{m}$  sensor (*lower S/N and ringing from digital*)
- Small pixels have worse performance, probably due to charge sharing effects (*pixel 5 tested in testbeam*)

# IN-LAB TIMING MEASUREMENTS WITH PMT AND $^{90}\text{Sr}$ SOURCE

Chip#6, pixel 8,  $0.5 \times 1 \text{ mm}^2$ ,  $200 \mu\text{m}$

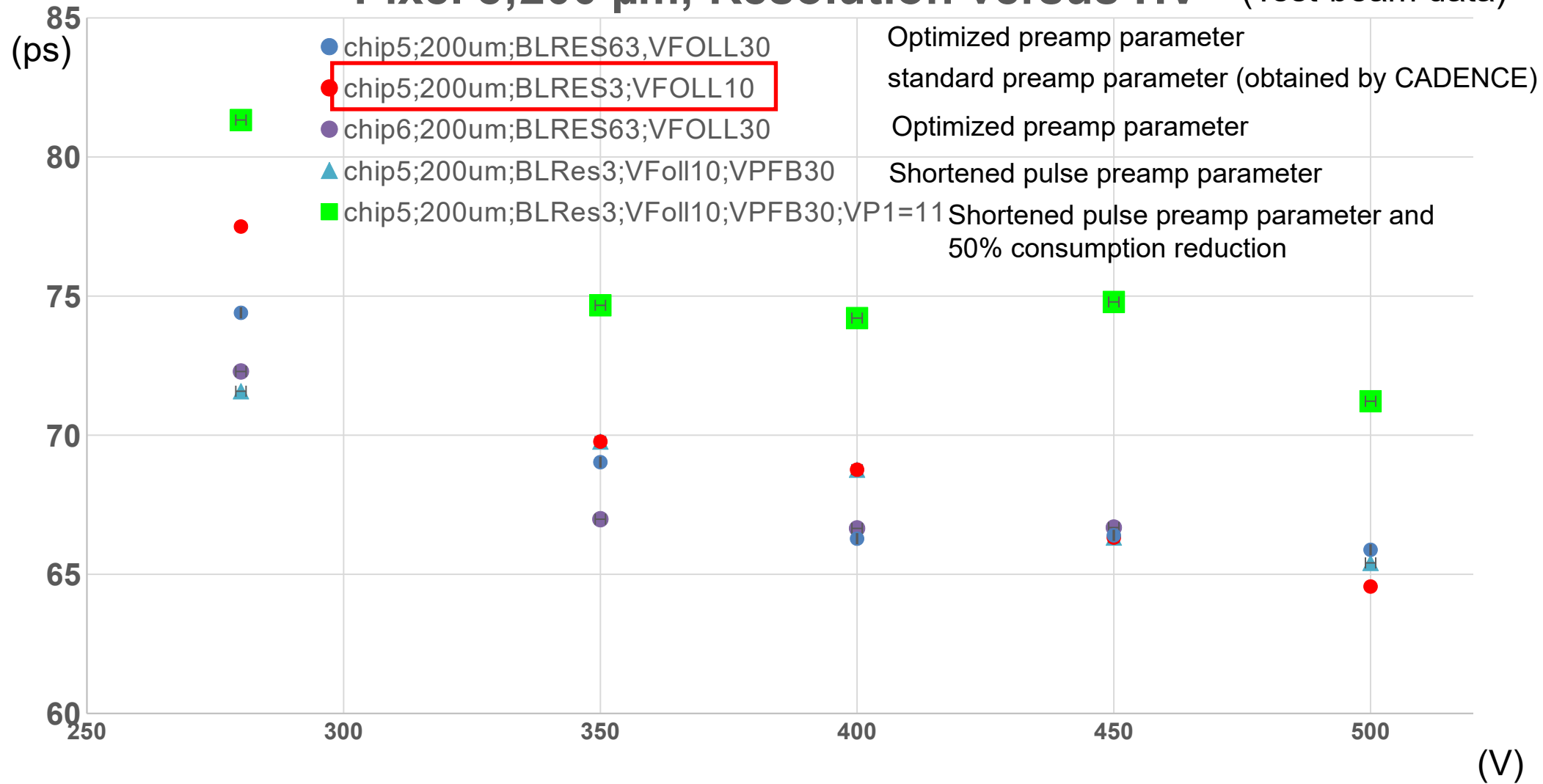


→ In-lab measurements with  $^{90}\text{Sr}$  betas allowed to predict actual performance with MIPs

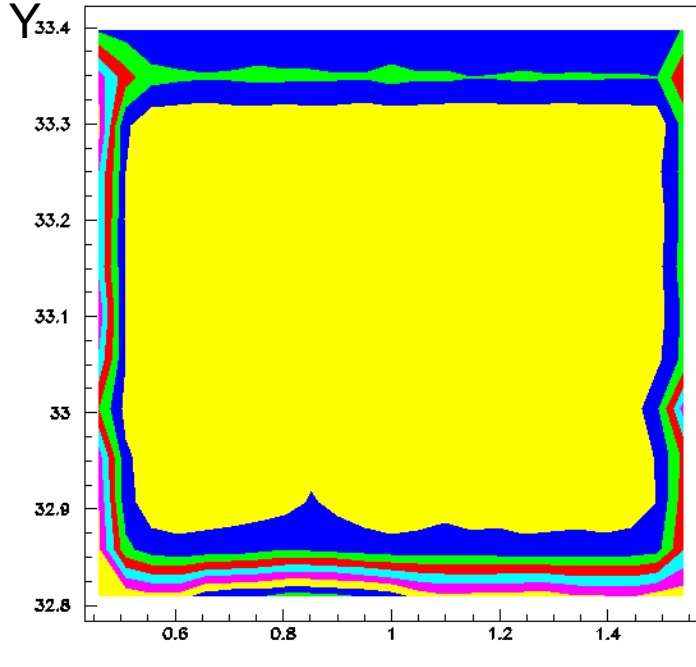


Have to select MIP-like betas by cutting out low energy deposits in PMT

# Pixel 8;200 $\mu\text{m}$ ; Resolution versus HV (Test-beam data)

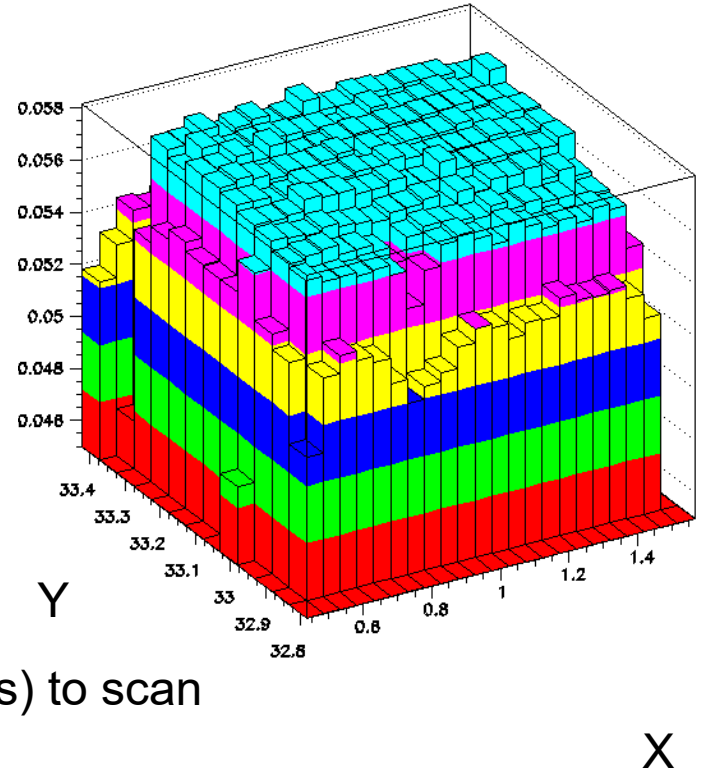


# Pixel position scan at 20 keV with photons (data taken at Synchrotron Soleil)



Amplitude

Pixel has very good uniformity



Used a pencil beam (50 microns by 50 microns) to scan pixel surface

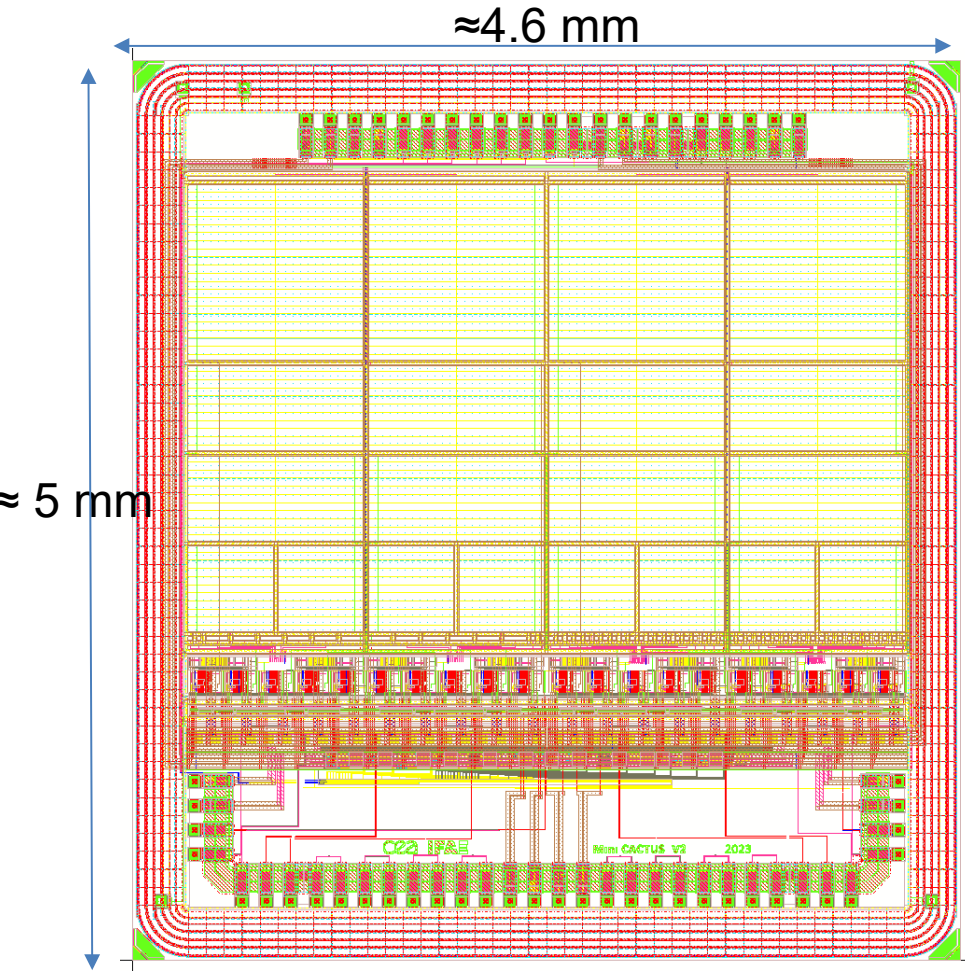
No non-uniformity found

Thanks to F. Orsini and A. Dawiec for the Beam line time and help with data taking !

# MiniCACTUS\_V2 Sensor Chip

Irfu : Yavuz Degerli, Fabrice Guilloux, Jean-Pierre Meyer, Philippe Schwemling

IFAE : Raimon Casanova, Yujin Gan, Sebastian Grinstein

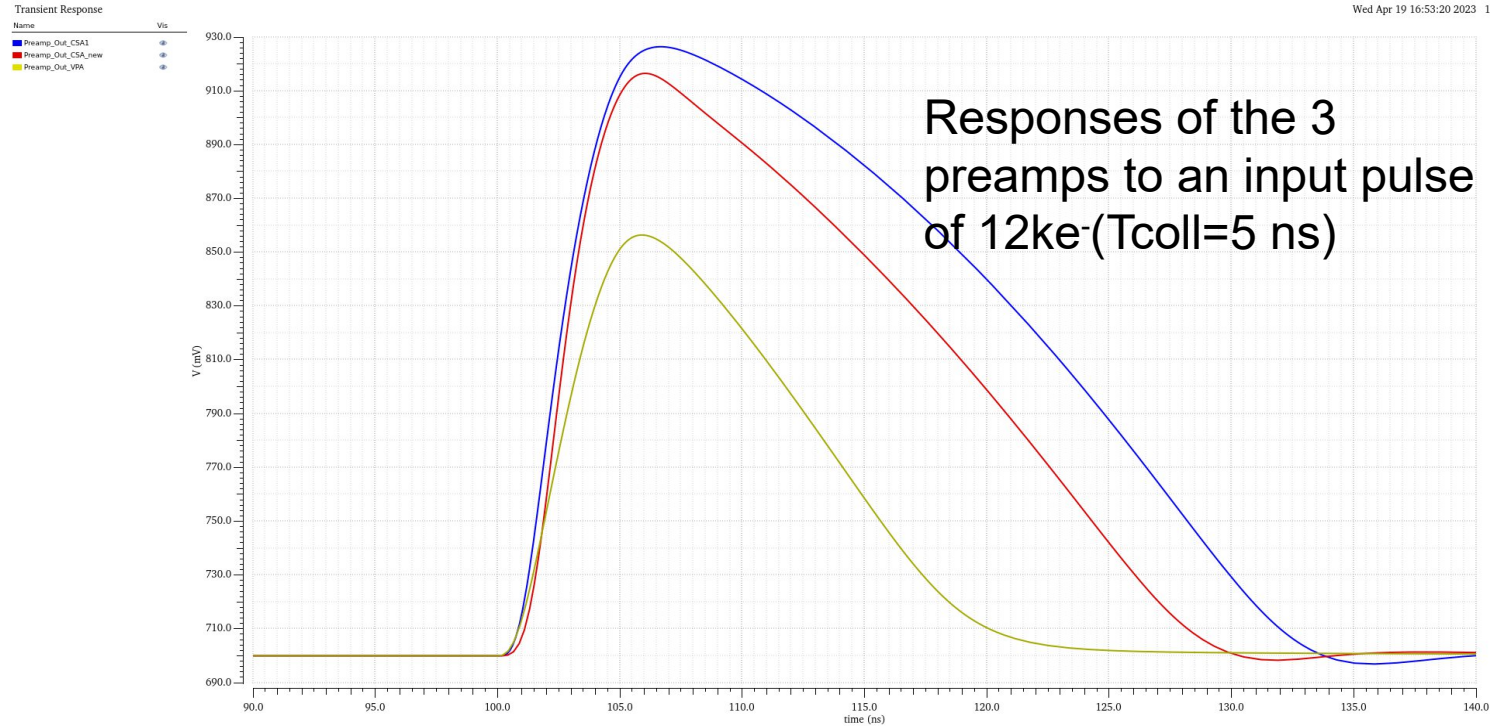


- ~ 2 times larger than MiniCACTUS
- 0.5 mm x 1 mm (baseline), 1 mm x 1 mm and 0.5 mm x 0.5 mm diodes
- 50  $\mu\text{m}$  x 150  $\mu\text{m}$  and 2 50  $\mu\text{m}$  x 50  $\mu\text{m}$  small test diodes
- 3 different preamps
- New multistage discriminator with **programmable hysteresis**
- Improved layout for better mixed-signal coupling rejection
- **CEA-IRFU & IFAE-Barcelona** coll.
- Submitted in May 2023, waiting for samples to
- come back from post-processing



# MiniCACTUS\_V2 Sensor Chip

- 3 different preamps implemented in MiniCACTUS\_V2
- 2 new preamps (CSA\_new and VPA) designed by **IFAE-Barcelona** for better jitter and reduced ToT



- **CSA1** : MiniCACTUS\_V1 charge sensitive preamp
- **CSA\_new** : new charge sensitive preamp
- **VPA** : new voltage preamp

# Monolithic CMOS and DRD3

WG1 research goals <2027	
	Description
RG 1.1	Spatial resolution: $\leq 3 \mu\text{m}$ position resolution
RG 1.2	Timing resolution: towards 20 ps timing precision
RG 1.3	Readout architectures: towards 100 MHz/cm <sup>2</sup> , 1 GHz/cm <sup>2</sup> with 3D stacked monolithic sensors, and on-chip reconfigurability
RG 1.4	Radiation tolerance: towards $10^{16} \text{ n}_{\text{eq}}/\text{cm}^2$ NIEL and 500 MRad

DRD3 WG1 Monolithic CMOS		Assess technology performance for each RG – handle technical solution options for strategic programs of LS4			
		time scale			
		2024	2025	2026	2027
		Foundry submissions and Milestones (MS)			
Research Goals	Timeline				
	Technologies				
	TPSCo (TJ) 65 nm	design MPw1.1	submit MPw1.1 mid-2025 design MPw1.2	evaluate MPw1.1 submit MPw1.2 Q4-2026	evaluate MPw1.2
	TJ/TSI 180 nm, LFoundry 110/150 nm, IHP 130 nm	design MPw1.1 submit MPw1.1 Q4-2024	evaluate MPw1.1 design MPw1.2	submit MPw1.2 Q1-2026	
Position precision RG1	TPSCo (TJ) 65 nm	electrode size/shape/pitch, process variants 12° ER splits, thin epitaxial layer, stitching optimized for high channel density (low pitch)		MS1 establish position precision versus technology, channel configuration and readout mode	MS5 handle technical solutions for Vertex Detector (ALICE-3, LHCb-2, Belle-3, CMS/ATLAS)
	TJ/TSI 180 nm, LFoundry 110/150 nm, IHP 130 nm	electrode size/shape/pitch, wafer type/thickness, process variants 8° ER or MLM splits			
Timing precision RG2	TPSCo (TJ) 65 nm	similar to RG1 optimized for fast signal collection speed and high S/N		MS2 establish time precision versus technology, channel configuration	1) high radiation tolerance/rate technologies > 65 nm 2) high channel density, stitching TPSCo 65 nm
	TJ/TSI 180 nm, LFoundry 110/150 nm, IHP 130 nm	similar to RG1 optimized for fast signal collection speed and high S/N including gain layer option			
Readout architecture common with DRD7 RG3	TPSCo (TJ) 65 nm	digital/binary, synchronous/asynchronous optimised to features of RG1 and RG2 at medium rates power distribution and control in large size stitched matrix		MS3 establish performance of readout variants for power consumption	MS6 handle technical solutions for Central Tracking (ALICE-3, EIC, LHCb-2, Belle-3), Timing Layers (ALICE-3, ATLAS, CMS) with stitching TPSCo 65 nm
	TJ/TSI 180 nm, LFoundry 110/150 nm, IHP 130 nm	digital/binary, synchronous/asynchronous optimised to features of RG1 and RG2 at medium and high rates			
Radiation tolerance RG4	TPSCo (TJ) 65 nm	process features in splits		MS4 establish radiation tolerance provide guidelines for choice of substrates	MS7 handle technical solutions for low power w/o and w/ precision timing, at medium and high rates
	TJ/TSI 180 nm, LFoundry 110/150 nm, IHP 130 nm	variants of substrates (Cz, epitaxial), resistivity, p-type and n-type			

- Ambitious research goals
- Agressive timeline
- Quite some technologies/foundry processes under consideration → no clear choice yet, very likely one given technology will not reach all goals

# Global trade-offs : time resolution is not everything

Name	Sensor	node	Pixel size	Temporal precision [ps]	Power [W/cm <sup>2</sup> ]
ETROC	LGAD	65	1.3 x 1.3 mm <sup>2</sup>	~ 40	0.3
ALTIROC	LGAD	130	1.3 x 1.3 mm <sup>2</sup>	~ 40	0.4
TDCpic	PiN	130	300 x 300 μm <sup>2</sup>	~ 120	0.45 (matrix) + 2 (periphery)
TIMEPIX4	PiN, 3D	65	55 x 55 μm <sup>2</sup>	~ 200	0.8
TimeSpot1	3D	28	55 x 55 μm <sup>2</sup>	~ 30 ps	5-10
FASTPIX	monolithic	180	20 x 20 μm <sup>2</sup>	~ 130	40
miniCACTUS	monolithic	150	0.5 x 1 mm <sup>2</sup>	~ 90-65 ps	0.15 – 0.3
MonPicoAD	monolithic	130 SiGe	25 x 25 μm <sup>2</sup>	~ 36	40
Monolith	LGAD monolithic	130 SiGe	25 x 25 μm <sup>2</sup>	~ 25	40

Table from  
N. Cartiglia  
(VCI 2022)

Trade off to be  
found between

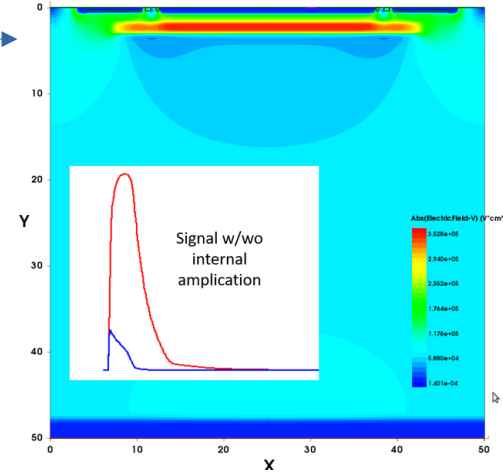
- Space resolution,
- time resolution
- power consumption
- Technology availability

50 ps @ 0.1W/cm<sup>2</sup>

# Conclusions and perspectives

Short term : evaluation of  $10^{15}$  1 MeV neq/cm<sup>2</sup> MiniCactus v1 :  $10^{14}$  (1 MeV neq/cm<sup>2</sup> (not shown here) have perf comparable to unirradiated chips if cooled at -15°C

- In-lab and test-beam tests of MiniCactus v2. Hope to correct analog/digital coupling and have improved timing performance !
- Medium term : investigate monolithic pixels with integrated gain layer.
- Possible with standard LF15A process, submission being prepared
  - Intrinsic gain would allow better timing performance and possibility of thinner sensors
- In general, a lot of activity underway on monolithic CMOS timing oriented sensor developments
  - Many technologies are being evaluated, see DRD3 WGs and WPs
- Present performance not far from what could be needed for a timing layer or a TOF detector
- Integration in an actual experiment needs :
  - Careful trade off evaluation between timing performance, space resolution, power dissipation
  - A lot of work to integrate digital data processing in a fully monolithic design
- Publications :
  - MiniCACTUS: A 65 ps Time Resolution Depleted Monolithic CMOS Sensor (arXiv:2309.08439, NSS 2022 conference)
  - MiniCACTUS: Sub-100 ps timing with depleted MAPS, Nucl.Instrum.Meth.A 1039 (2022) 167022, VCI 2022 conference)
  - CACTUS: A depleted monolithic active timing sensor using a CMOS radiation hard technology (arXiv:2003.04102, JINST 15 (2020) 06, P06011)

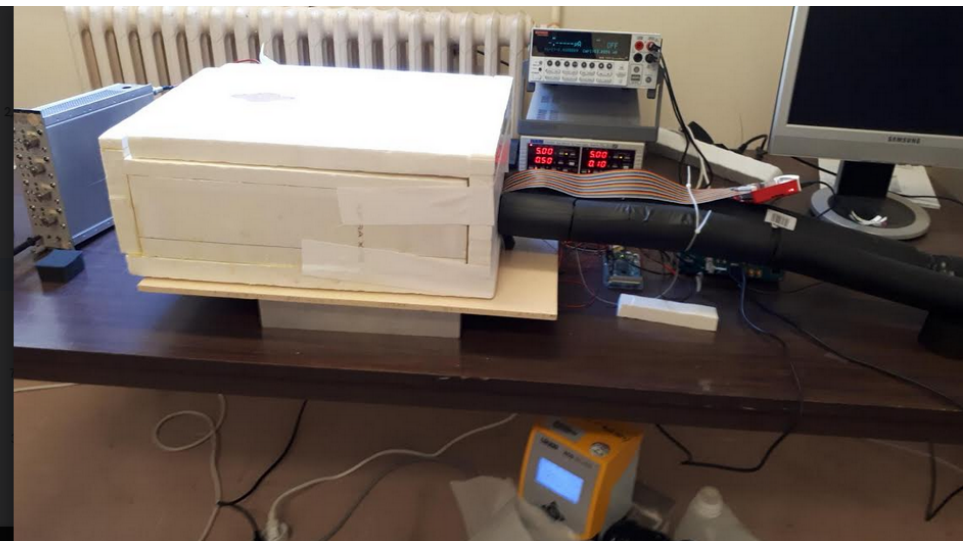


# Backup

# Development of cold box setup

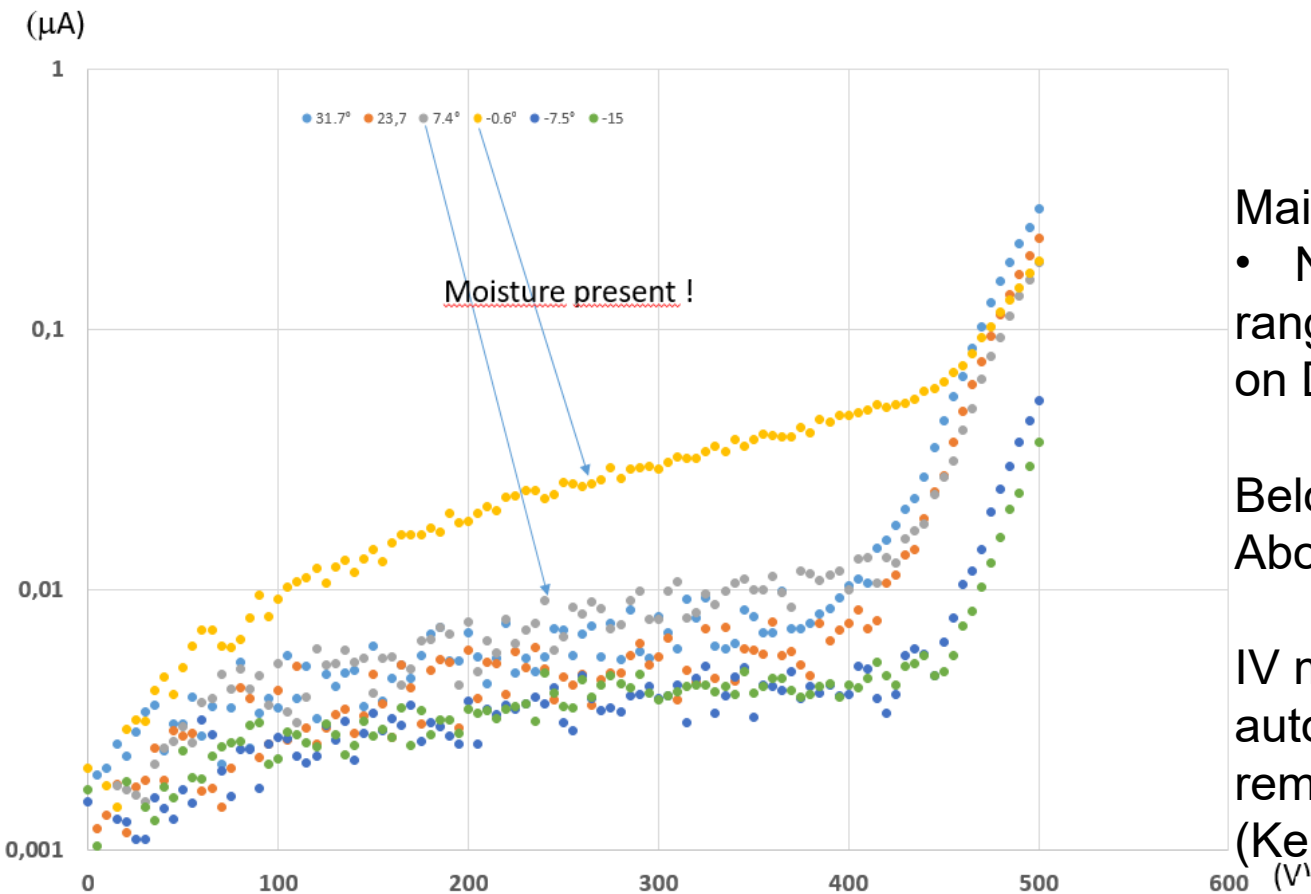


Initial status After one month of continuous operation at  $-15^{\circ}\text{C}$



- Mostly intended to test irradiated samples
  - We have  $100\ \mu$  and  $300\ \mu$  irradiated at  $10^{14}$ ,  $10^{15}$ ,  $10^{16}$   $1\ \text{MeV neq/cm}^2$
- MiniCactus testbench (DUT board, GPAC, Raspio) in insulating foam box (plus feedthroughs for power and cooling)
  - Copper plate with a cooling pipe welded to it plus copper fingers bring cold surface as close as possible to DUT
- Monitoring of temperature and moisture level at various places in cold box
- No moisture control, we just try to minimise water input
- LAUDA chiller, min temp  $-30^{\circ}\text{C}$  at chiller output
- Kapton windows allow use of  $90\text{Sr}$  beta source (has to stay outside of cold box for safety/regulatory reasons)

# IV curves vs temperature (Unirradiated DUT. 300 $\mu$ thick)



Main conclusion :

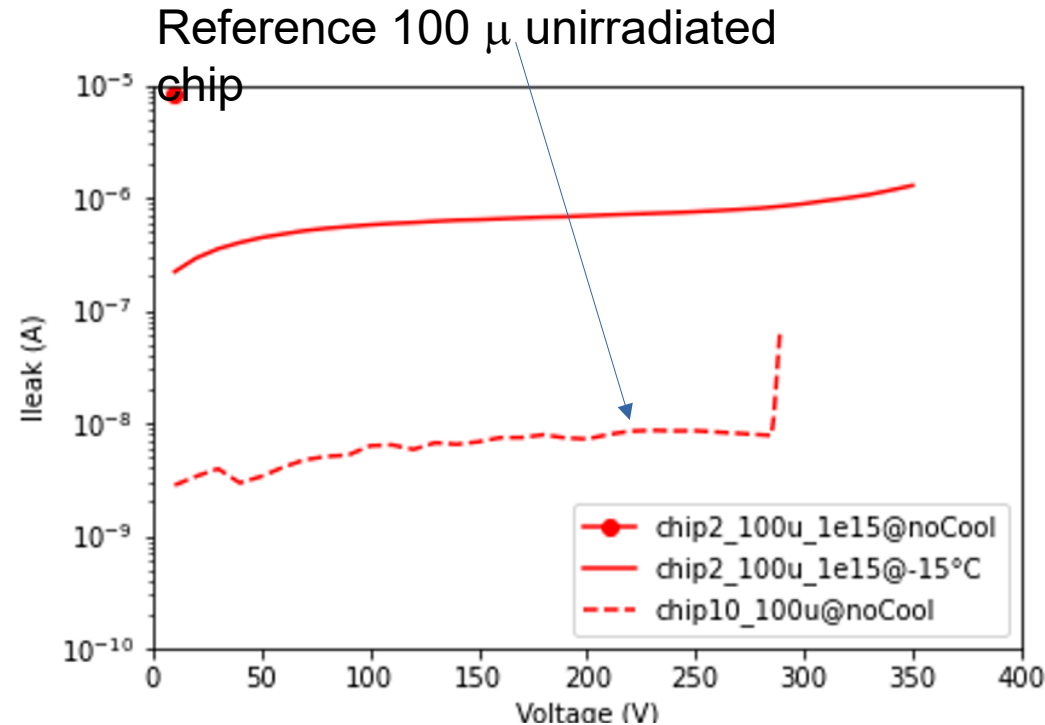
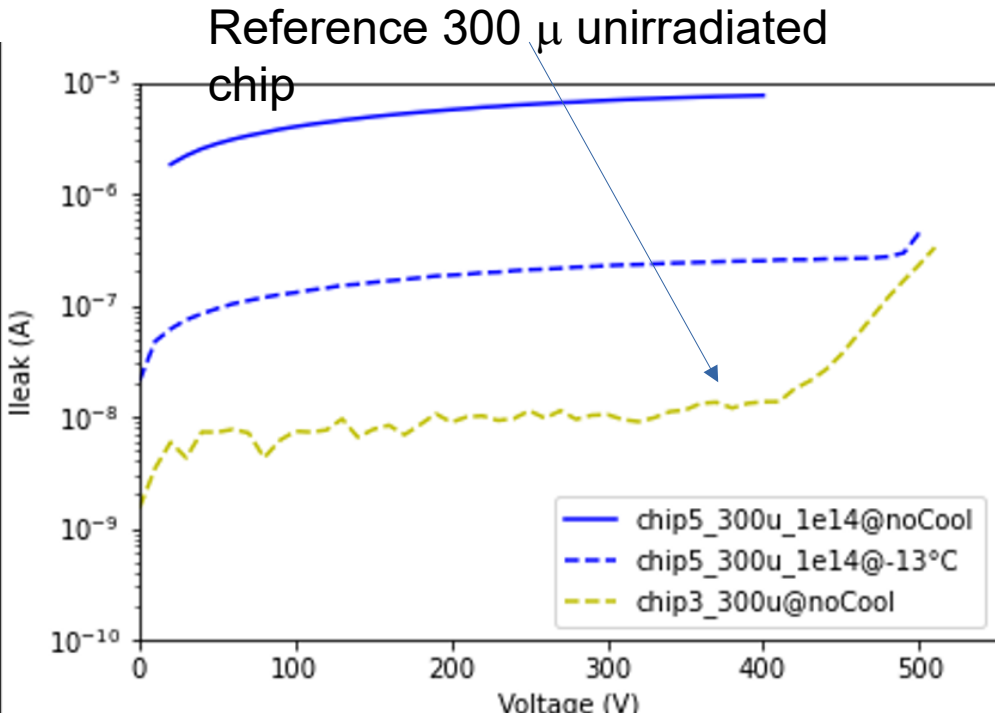
- Need to run avoiding temperature range between 7.5°C and -1°C measured on DUT

Below -1°C all water is frozen  $\rightarrow$  OK

Above 7.5°C all water is vapour  $\rightarrow$  OK

IV measurement done routinely and automatically through remote control and monitoring of HV PS (Keithley sourcemeter)

# IV curves of irradiated MiniCactus v1



As expected, BV increases with total dose

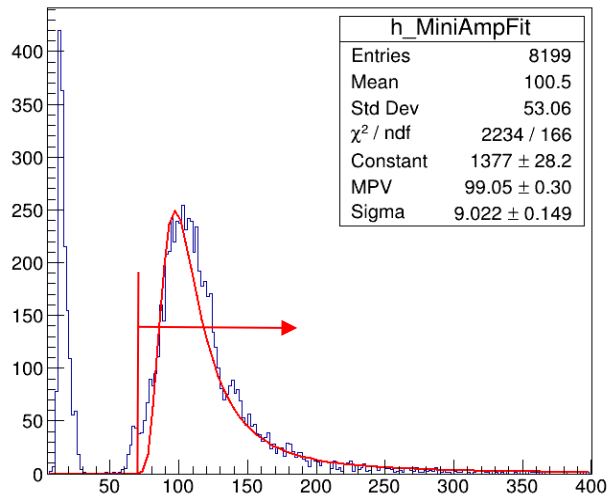
Cooling is essential to bring leakage current to manageable values



# PMT and MiniCactus data

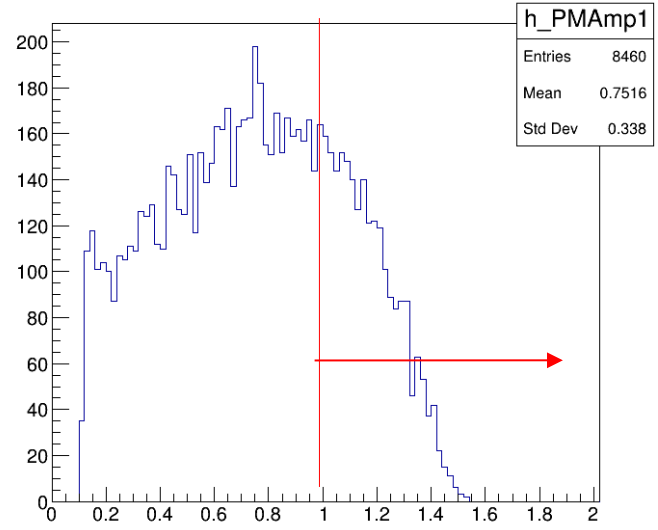
$10^{14}$  1 MeV neq irradiated DUT, 300  $\mu$  thick, 200V

Fitted AmpOut (mV)



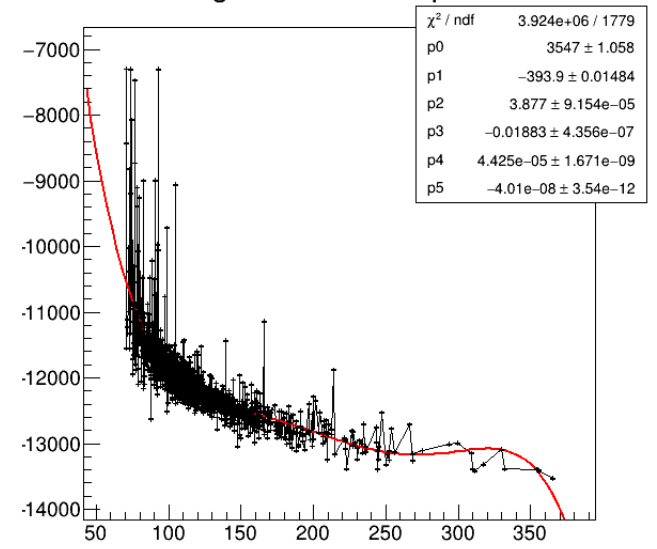
Amplitude  
(mV)

PMT1 (bottom) Amplitude



Amplitude  
(V)

Digital-PMT vs AmpOut

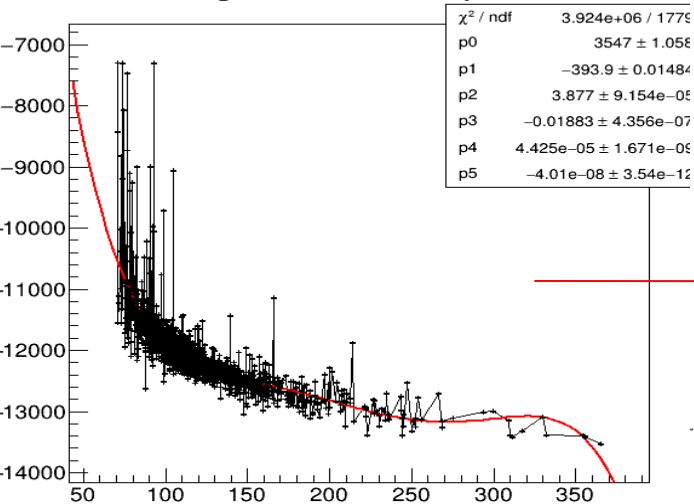


TW correction  
As a fct of analog  
amplitude

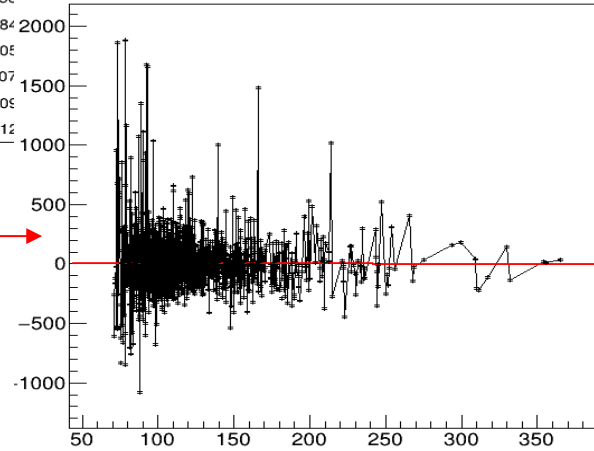
# PMT and MiniCactus data

$10^{14}$  1 MeV neq irradiated DUT, 300  $\mu$  thick, 200 V

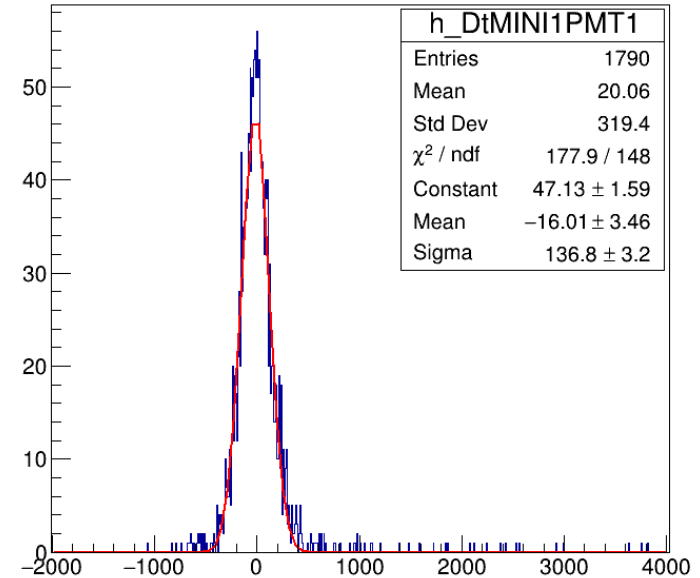
Digital-PMT vs AmpOut



Digital-PMT vs AmpOut

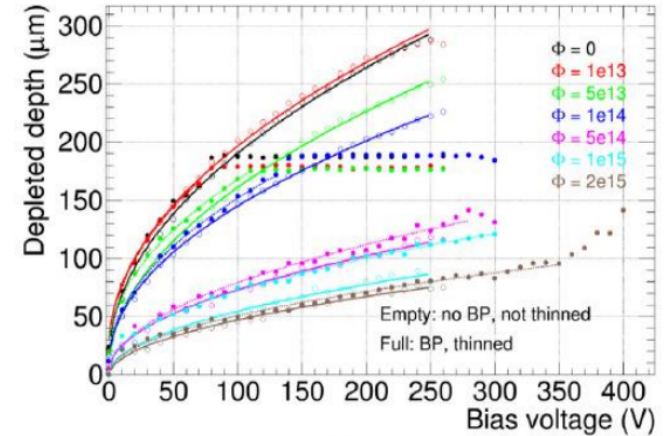
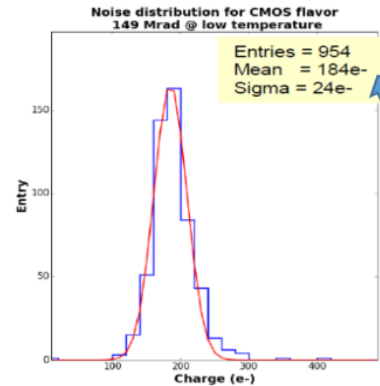
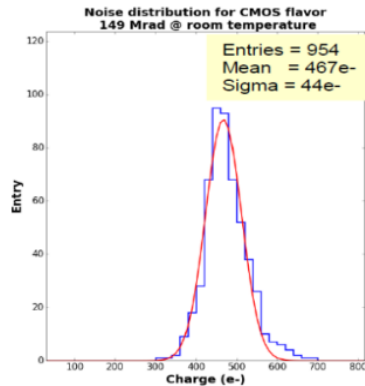
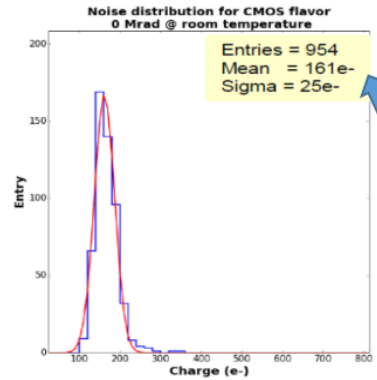
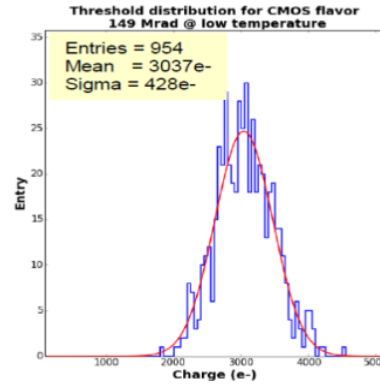
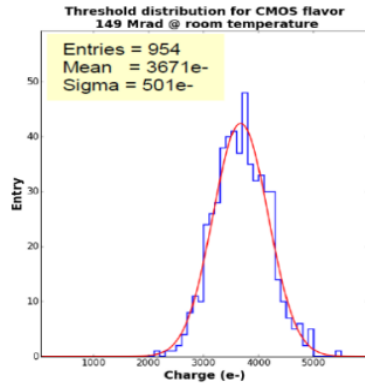
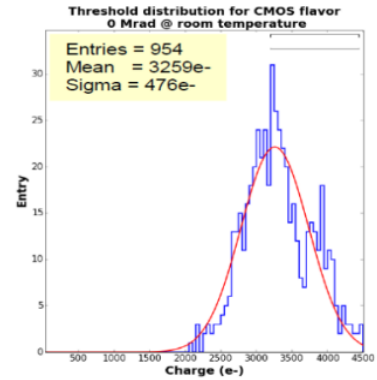


DT PMT1-MIN1 (ps)



# LF15A radiation hardness

0 Mrad @Room Temp   149 Mrad @Room Temp   149 Mrad @Low Temp -15°C



[I. Mandic et al. NIM A 903, 2018]

→ Radiation tests at CERN-SPS with **proton** beam on **LF-CPIX** chip (CPPM)

→ 14% increase of noise after irradiation with cooling

# Comparison of time resolution of unirradiated and $10^{14}$ 1 MeV neq chips



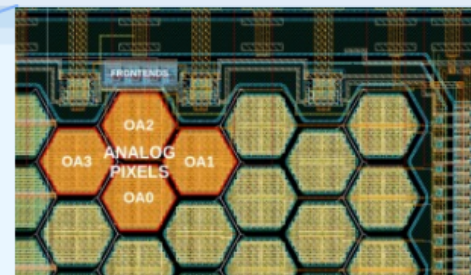
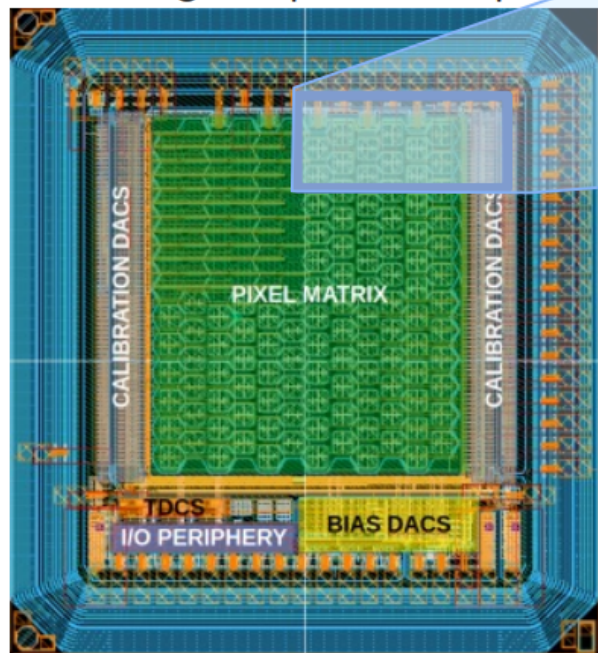
Sensor	HV bias (V)	Conditions	Temp. (°C)	Time res. (ps)	MPV (mV)
Unirradiated 300 u	400	testbeam, MCPMT time reference	room	$78.97 \pm 1.36$	$201.9 \pm 0.5$
Unirradiated 300 u	400	90Sr, PMT time reference*	room	$104.5 \pm 2.30$	$195.7 \pm 2.3$
Unirradiated 300 u	280	testbeam, MCPMT time reference	room	$89.11 \pm 1.56$	$200.9 \pm 0.5$
Irradiated 300 u	280	90 Sr, PMT time reference	20	$108.2 \pm 3.2$ (PMT sub.)	$108.2 \pm 3.2$
Irradiated 300 u	320	90 Sr, PMT time reference	20	$132.9 \pm 5.0$ (PMT sub.)	$113.5 \pm 0.8$
Irradiated 300 u	320	90 Sr, PMT time reference	-15	$87.9 \pm 4.7$ (PMT sub.)	$132.7 \pm 0.6$

Irradiation at  $10^{14}$   $n_{eq}$  worsens time resolution by 18 % w.r.t. unirradiated at 20 °C

Cooling at -15°C brings time resolution more or less back to unirradiated performance (less dark current fluctuations)

\*PMT resolution for 90 Sr betas estimated to be  $71.3 \text{ ps} \pm 1.7 \text{ ps}$

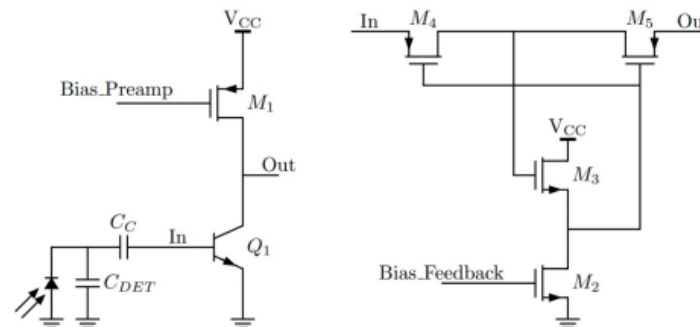
100 $\mu\text{m}$  pitch hexagonal pixels - 25  $\mu\text{m}$  depletion



## UNDER TEST HERE

### Analog Channels:

HBT preamp + two HBT Emitter Followers to 500 $\Omega$  Resistance on pad.



MPW submission in 2019 funded by H2020



*G. Iacucci et al 2022 JINST 17 P02019*



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Department of Nuclear and  
Particle Physics

# Leading-edge technology: **IHP SG13G2**

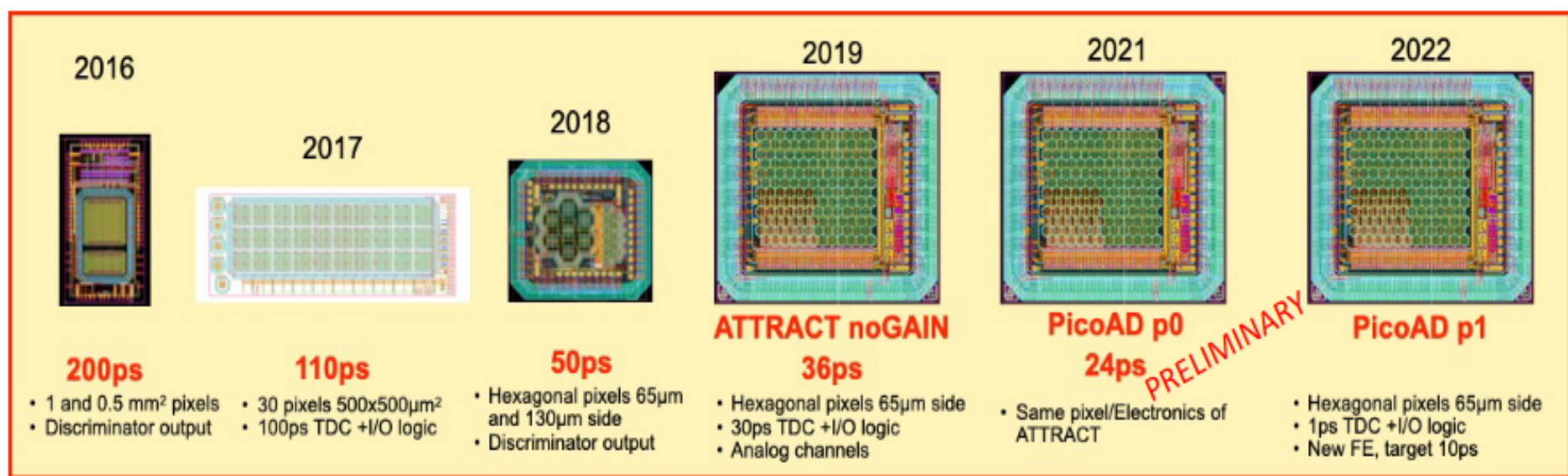
**130 nm** process featuring **SiGe HBT** with

- Transistor transition frequency:  $f_t = 0.3 \text{ THz}$
- DC Current gain:  $\beta = 900$
- Delay gate: **1.8 ps**



innovations  
for high  
performance  
microelectronics

Leibniz-Institut für  
innovative Mikroelektronik

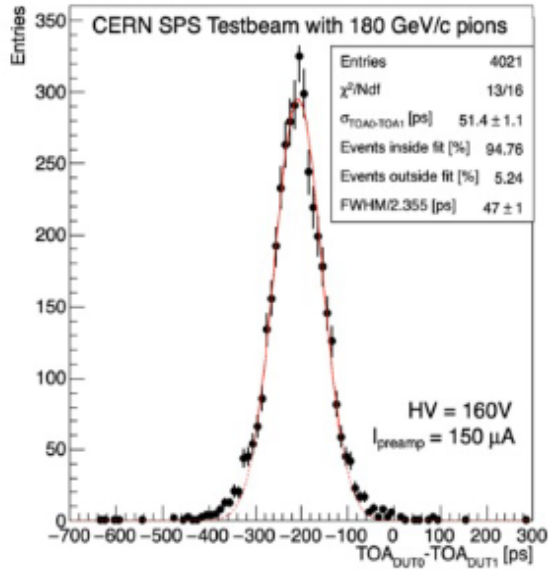


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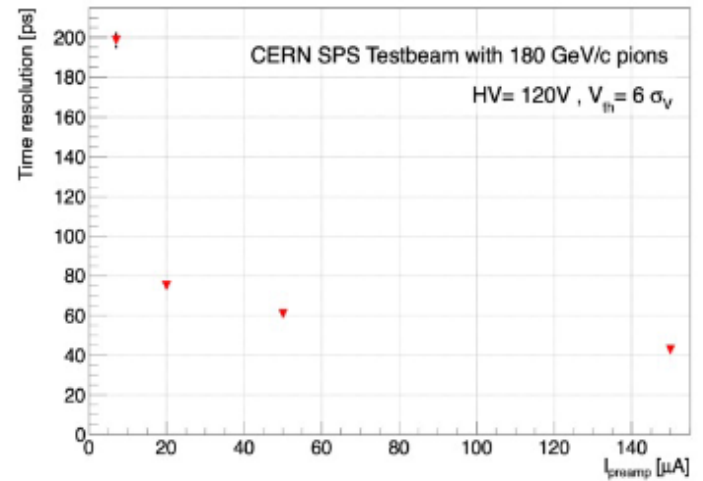
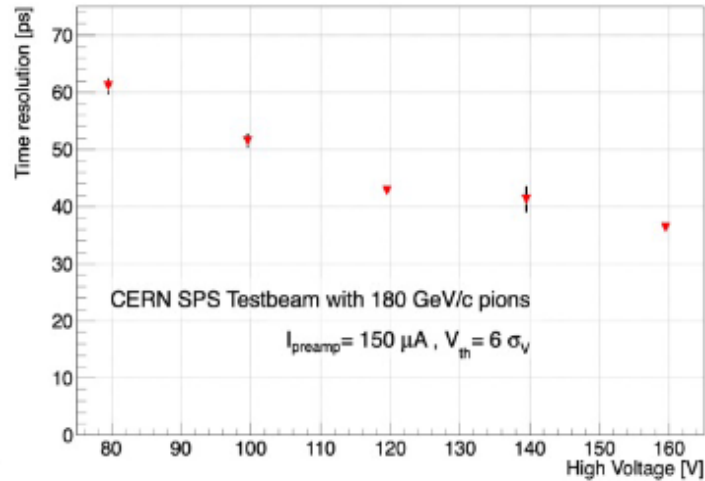
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Department of Nuclear and  
Particle Physics



# ATTRACT prototype – Time Stamping



## Time of flight between DUT0 and DUT1



- 57 ps after  $10^{16}$  1 MeV neq/cm<sup>2</sup>

$$\sigma_t = \frac{\sigma_{TOA0-TOA1}}{\sqrt{2}} = (36.4 \pm 0.8) \text{ps} \text{ without gain structure}$$

- can be brought back to 40 ps, with HV and LVPS increase :  
Arxiv : 2310.19398

24 ps with gain layer (but complicated manufacturing → mass scale production ???)



# Fastpix (CERN) : sub-ns timing with TJ180

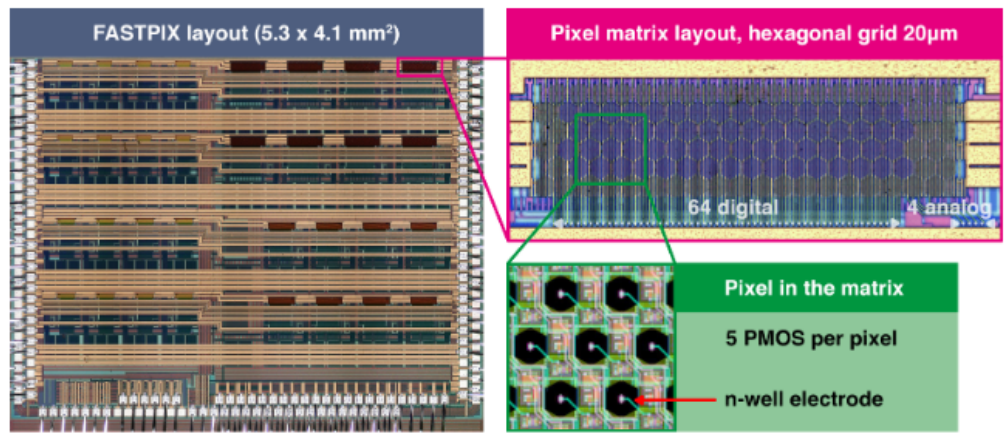


Figure 2. FASTPIX layout (5.3 mm × 4.1 mm) with details of the 20 µm pitch hexagonal grid zoom on 7 pixels.

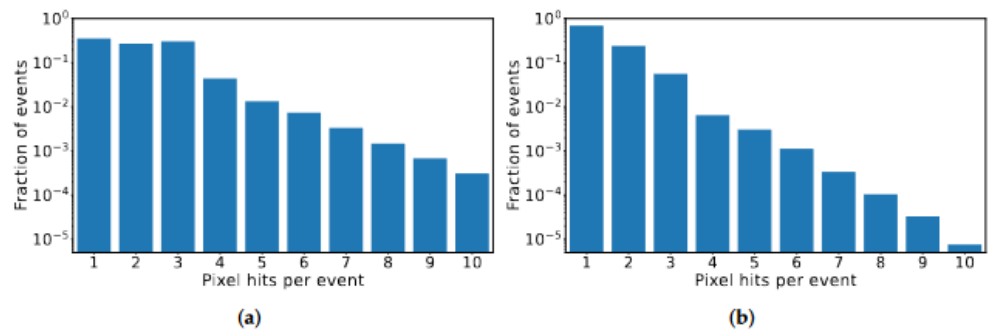


Figure 8. Number of pixel hits per event for the 10 µm (a) and 20 µm (b) pitch matrix.

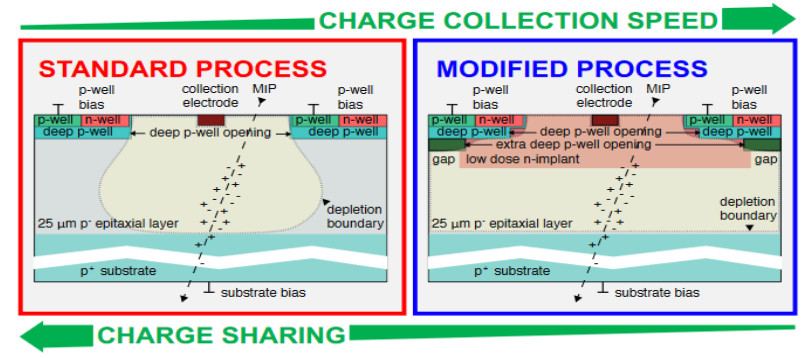


Figure 2. Wafer production process variants for FASTPIX represented by schematic cross-sections of the pixel unit cells, showing a cut perpendicular to the sensor surface. The standard 180 nm CMOS imaging process (left) and the modified process variant (right) with added low-dose n-type implant and optimizations such as a gap in the n-implant, retracted deep p-well and additional extra-deep p-well implant.

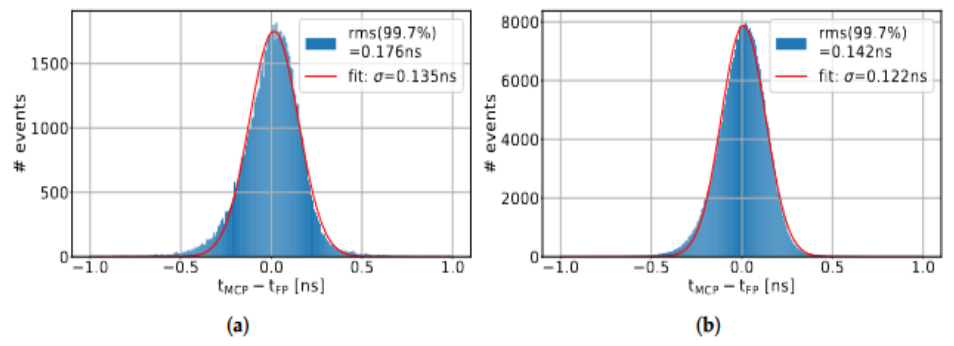
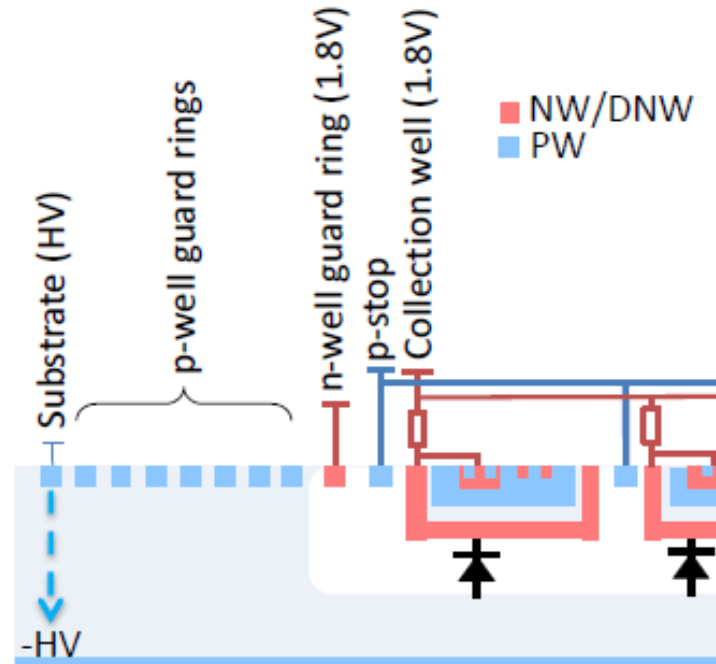


Figure 14. Seed-pixel time residuals after timewalk correction for the inner region of the 10 µm (a) and 20 µm (b) pitch matrix.

Plan to port and test the concept on TPSCo 65 technology, but small pixels → beware of drift field inhomogeneity !

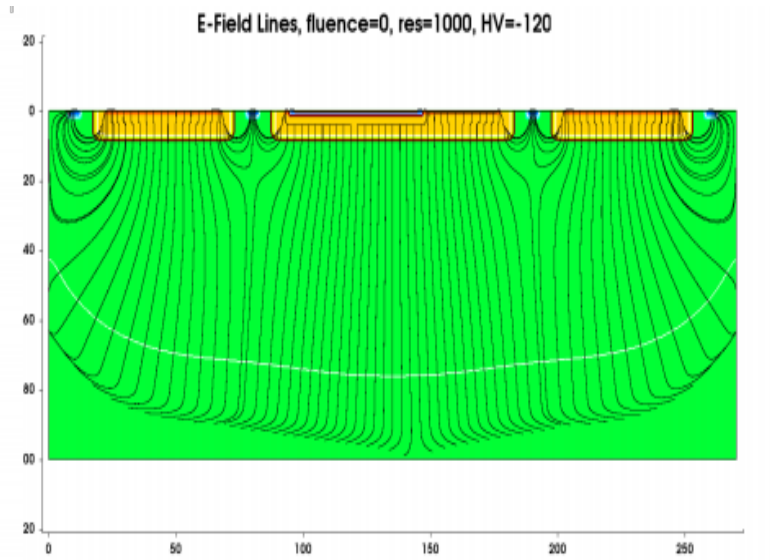
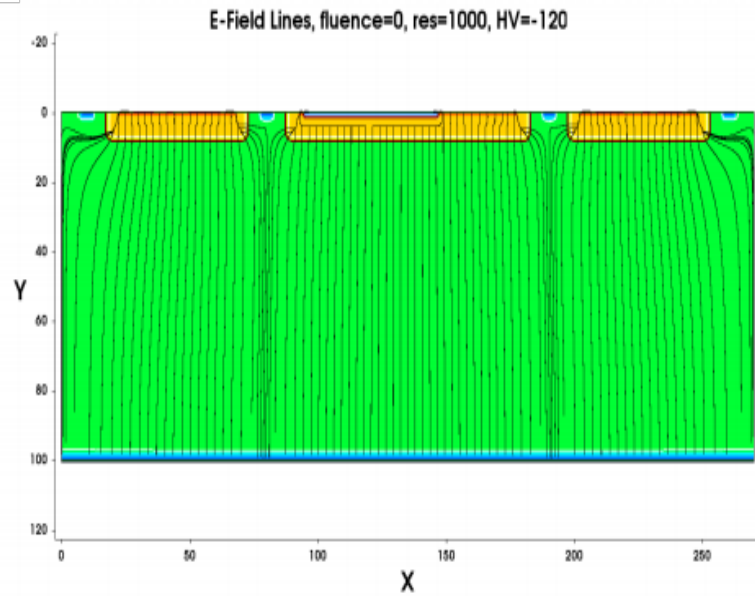


# GUARD-RINGS OF LF-MONOPIX1



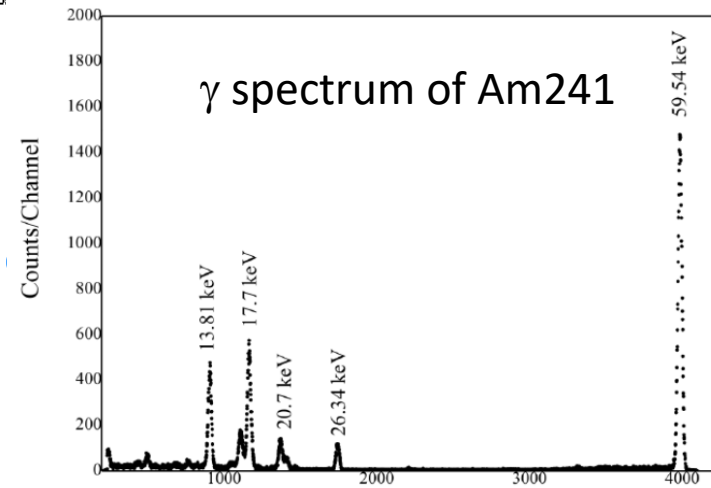
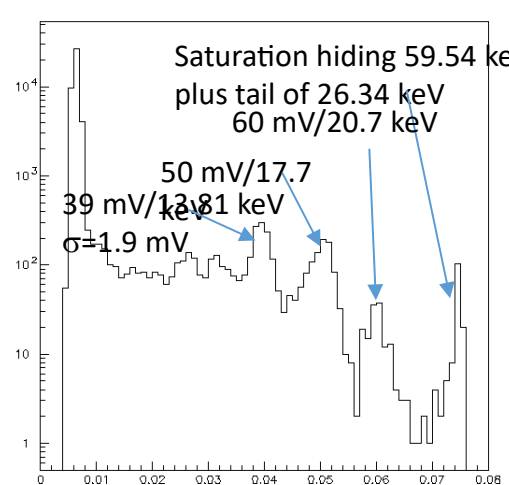
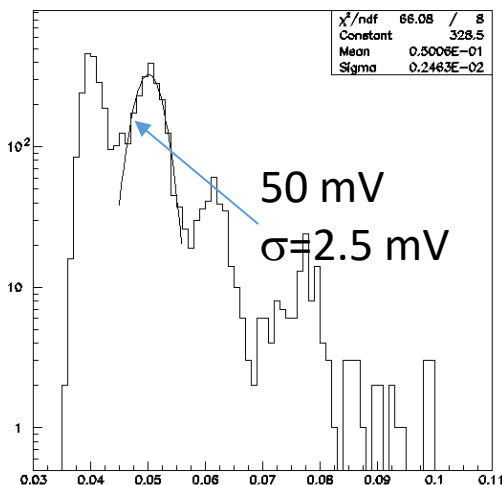
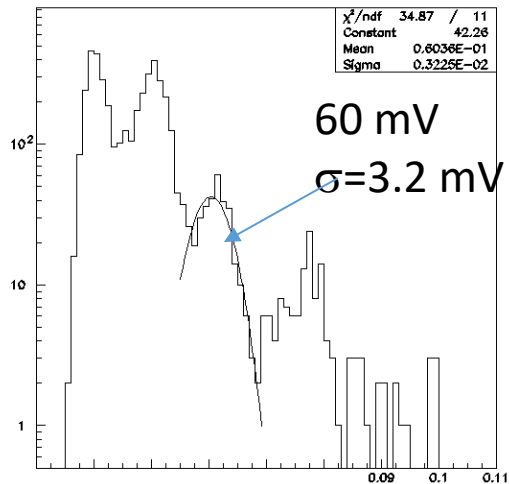
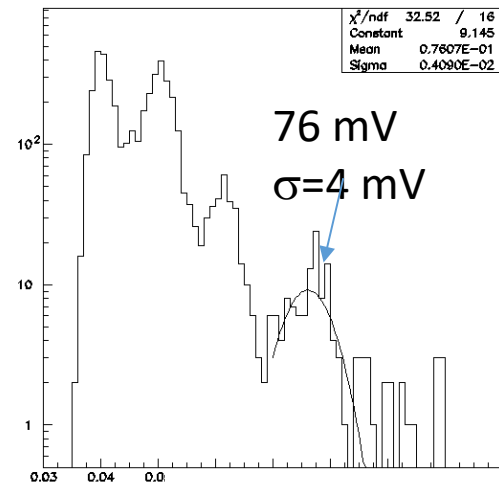
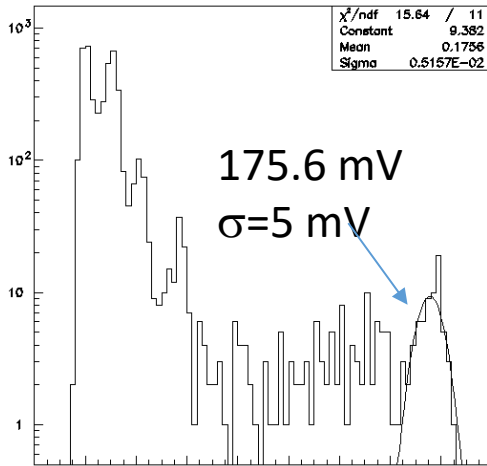
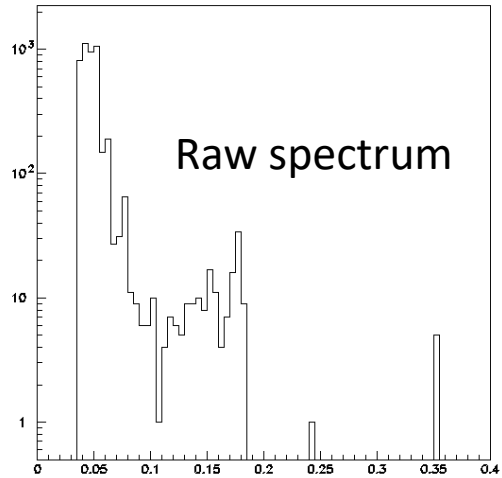
[[M. Barbero et al. JINST 15, 2020](#)]

# ELECTRIC FIELDS



Backside versus top biasing → Need backside polarization to ensure best charge collection and signal shape uniformity!

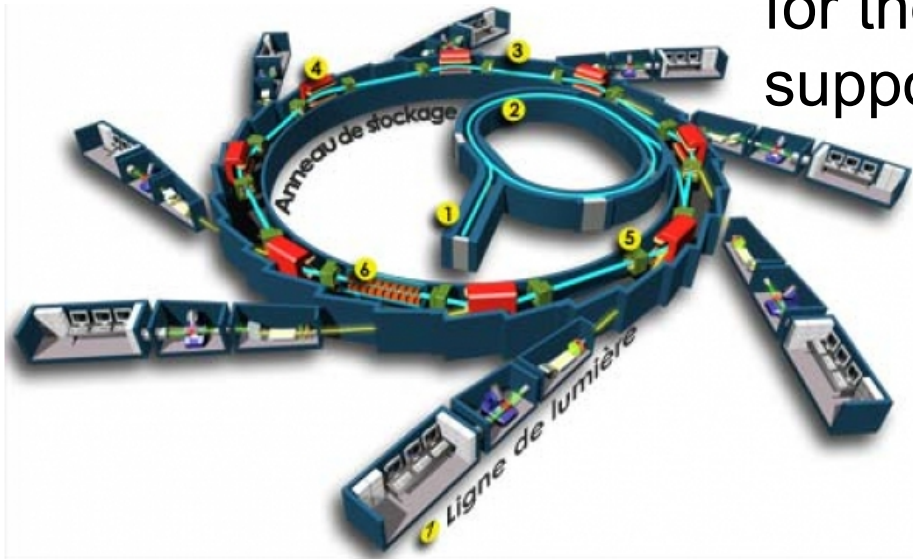
# 241Am Amplitude Spectrum (pixel 5, 50 $\mu\text{m}$ x 150 $\mu\text{m}$ )



# Test-beam at Synchrotron Soleil

June 2022

Many thanks to Fabienne Orsini and  
Arkadiusz Dawiec  
(Synchrotron Soleil)  
for the beam time and the technical  
support !

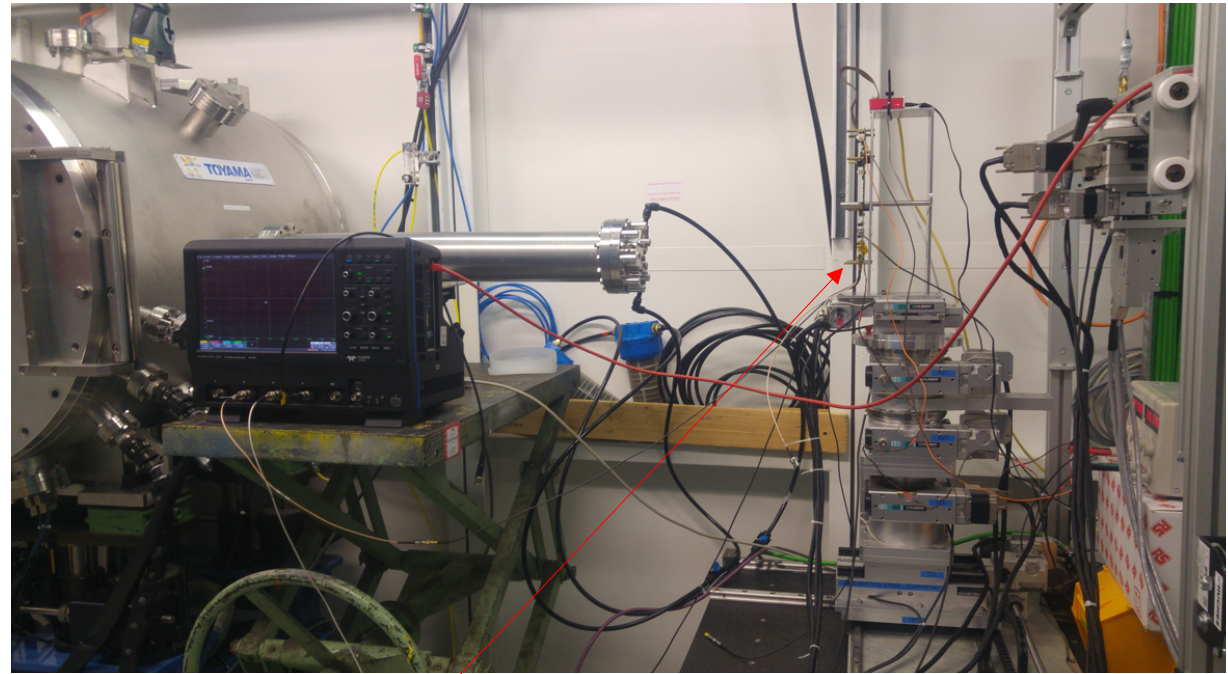
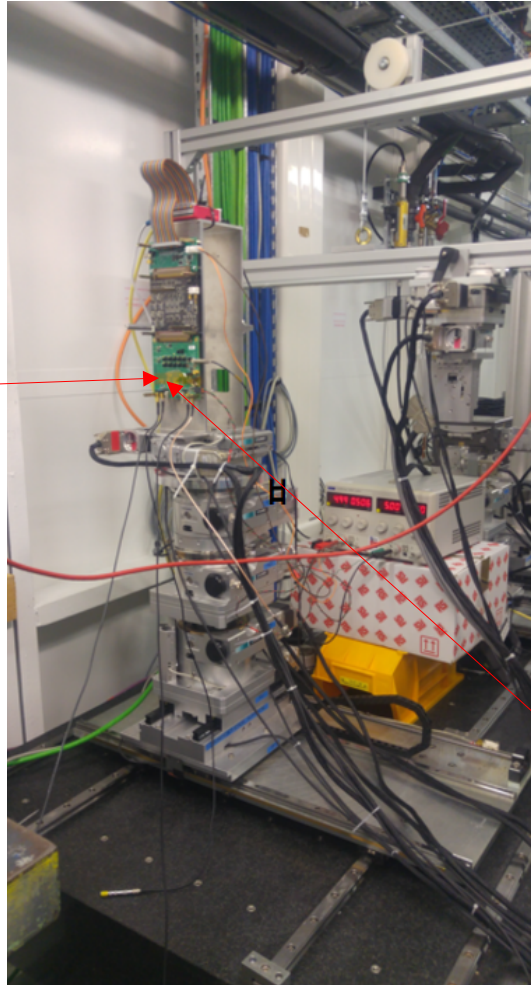


Photon beam is bunched : 90 ps pulse length  
Every 2.6 ns

Allows to study energy and time response  
Beams of 10 keV, 20 keV, 30 keV, 40 keV  
Available, attenuated to have  $\approx 1$   
photon/bunch

With X/ $\gamma$ radioactive sources, only energy  
response can be studied

# Setup pictures

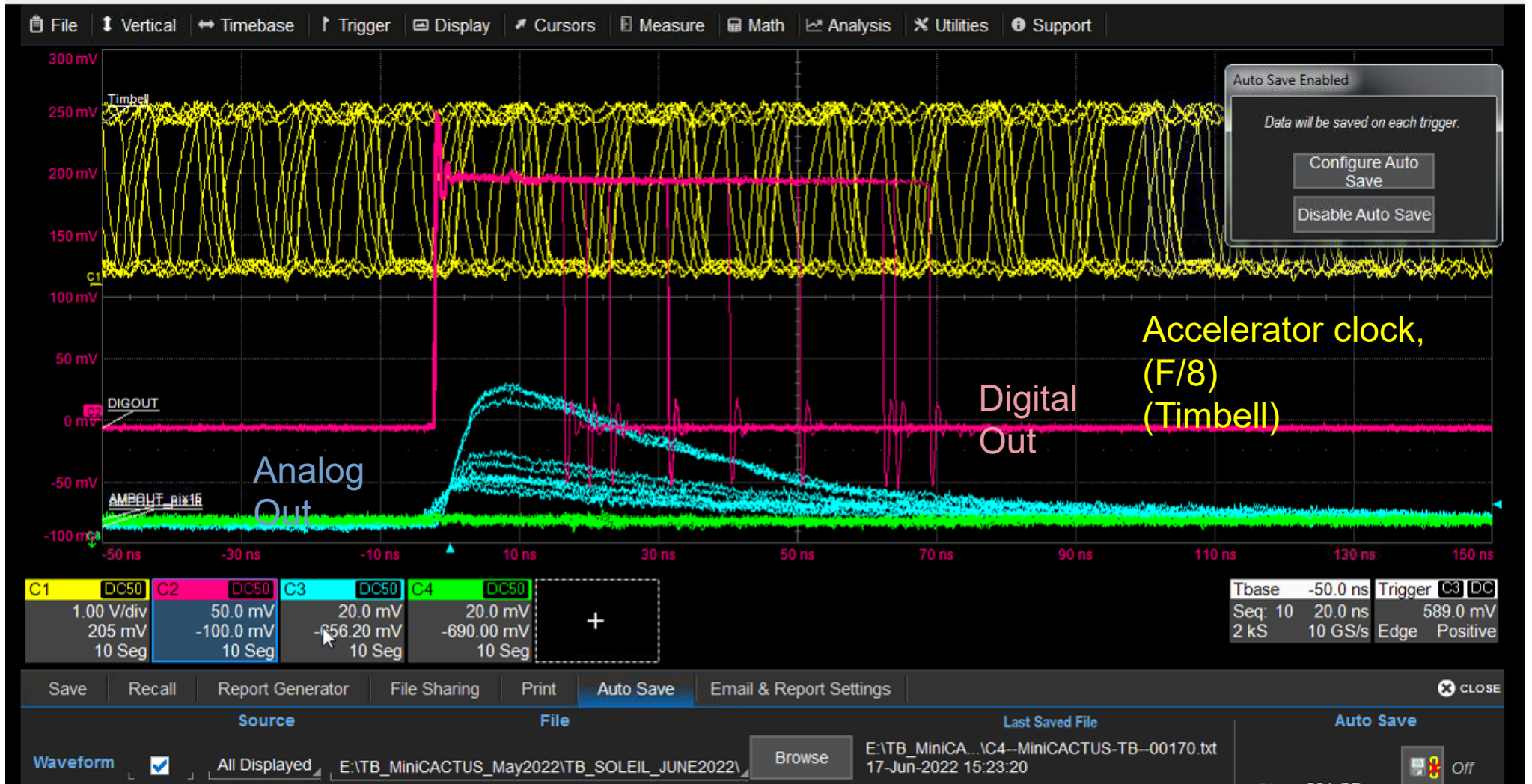


Beam  
direction

MiniCactus chip

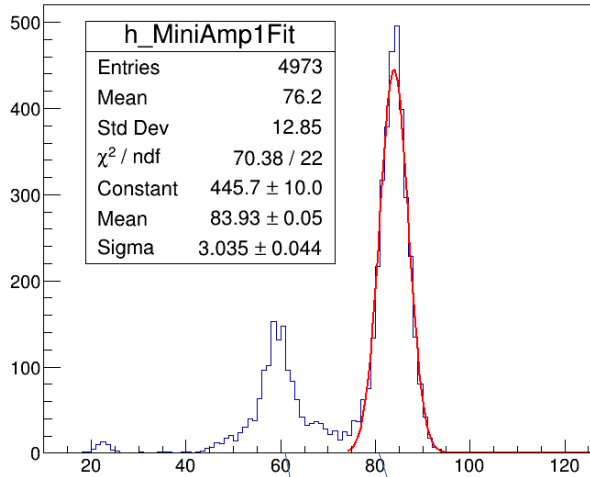
Data acquired with LeCroy  
oscilloscope,  
at 10 GSPS, 8 bits

# Typical waveforms



# Energy spectra at Soleil

Fitted AmpOut1 (mV)

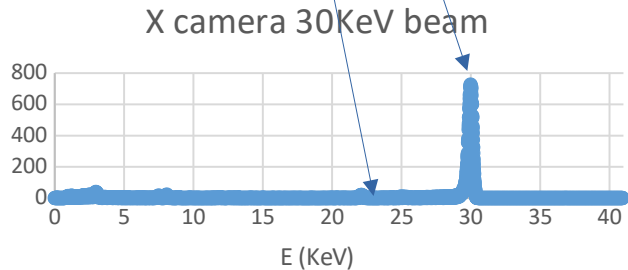


Parasitic energy peaks  
observed in MiniCactus

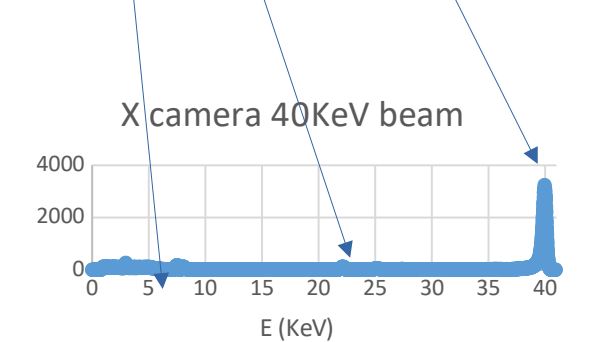
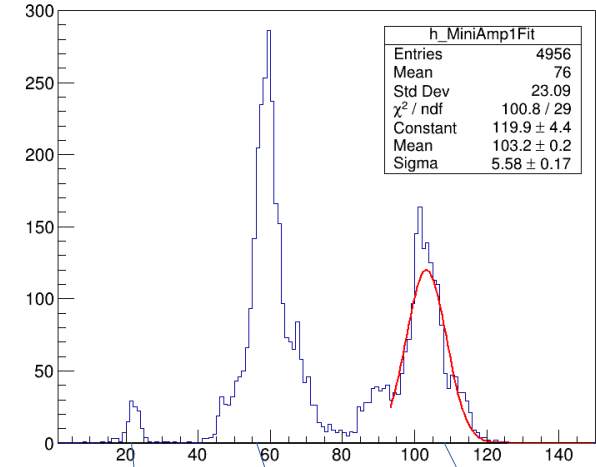
Their existence is confirmed  
by a dedicated camera  
installed  
on the beam line

Most probably due to  
fluorescence  
of PCB material (close to  
MiniCactus)

Camera sees different  
amplitude due  
to solid angle effect



Fitted AmpOut1 (mV)

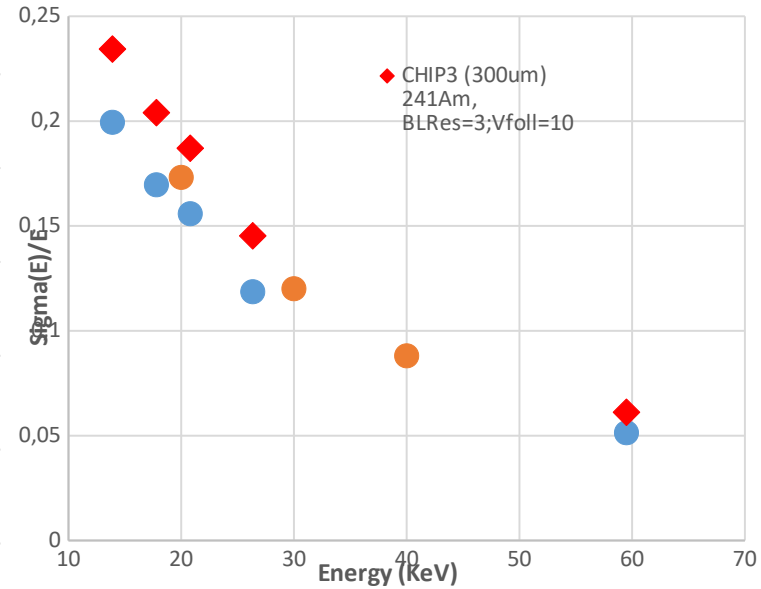
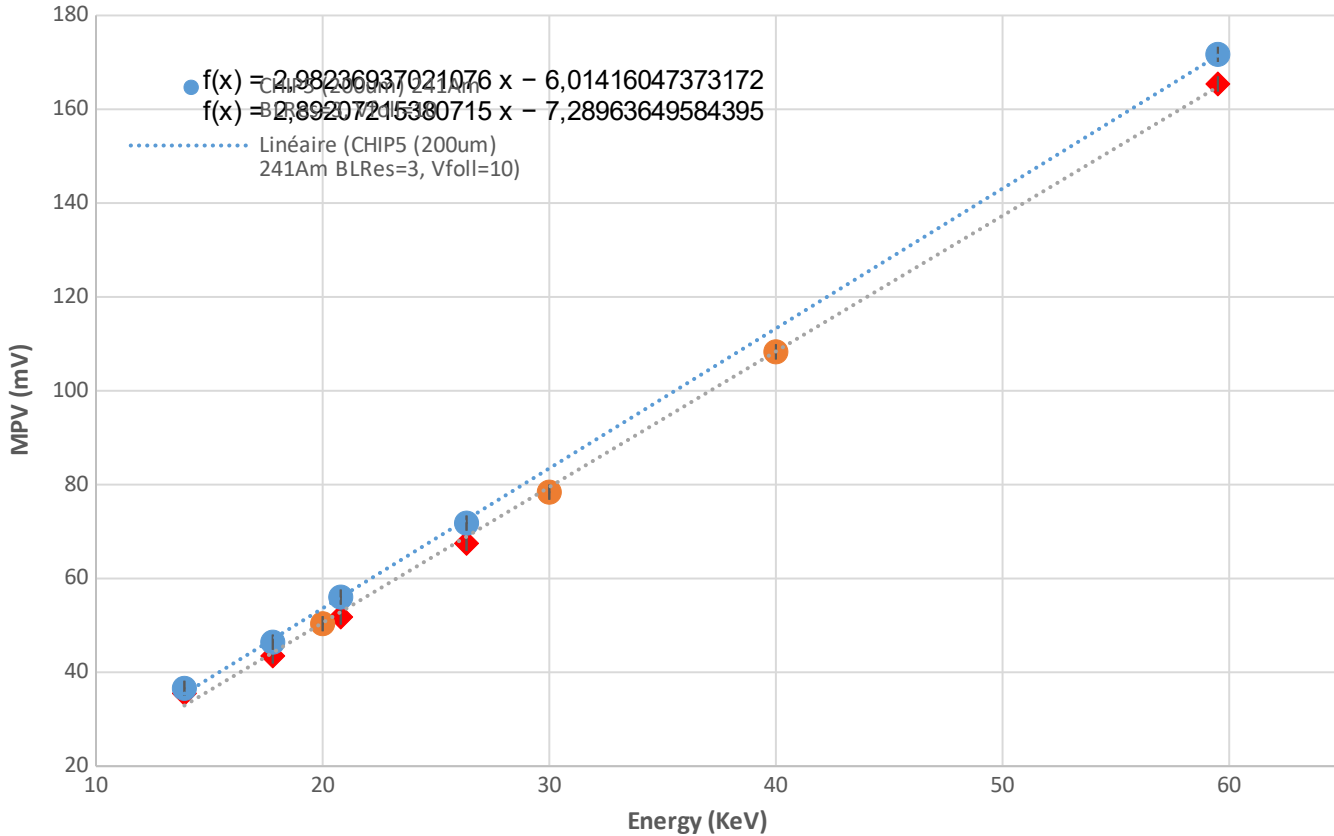


# Calibration comparison between Soleil data and 241Am X-ray lines

200  $\mu$  chip, 241Am data (200 V), px 8

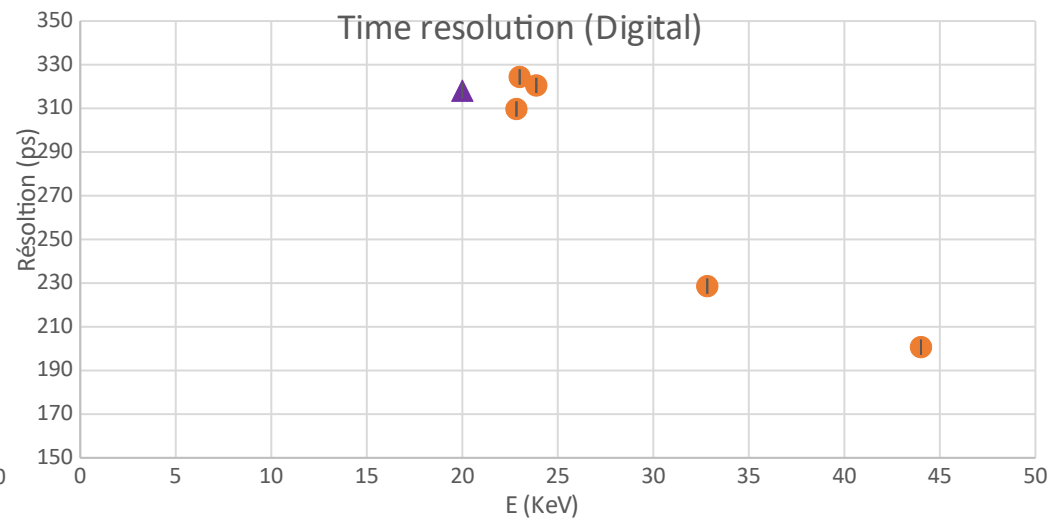
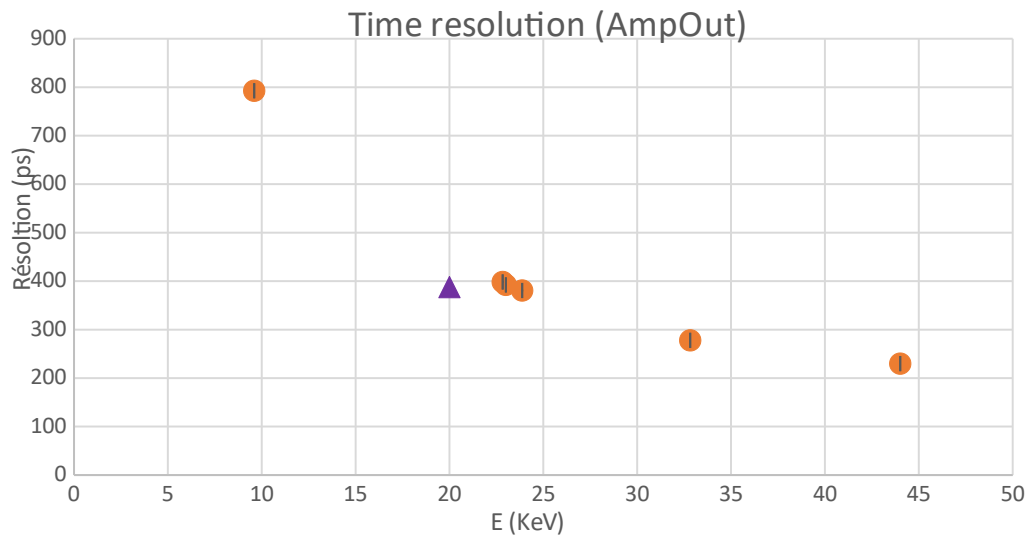
300  $\mu$  chip, Soleil data (400 V), px 8

300  $\mu$  chip, 241Am (300 V)





# Time resolution with photons



Time resolution worse for photons than for MIPs, at similar S/N

40 keV photon ( $\approx 200$  ps) releases similar charge as a MIP ( $\approx 65$  ps)

Interpreted as due to the different structure of energy deposits :

Pointlike for photons, along a line for MIPs